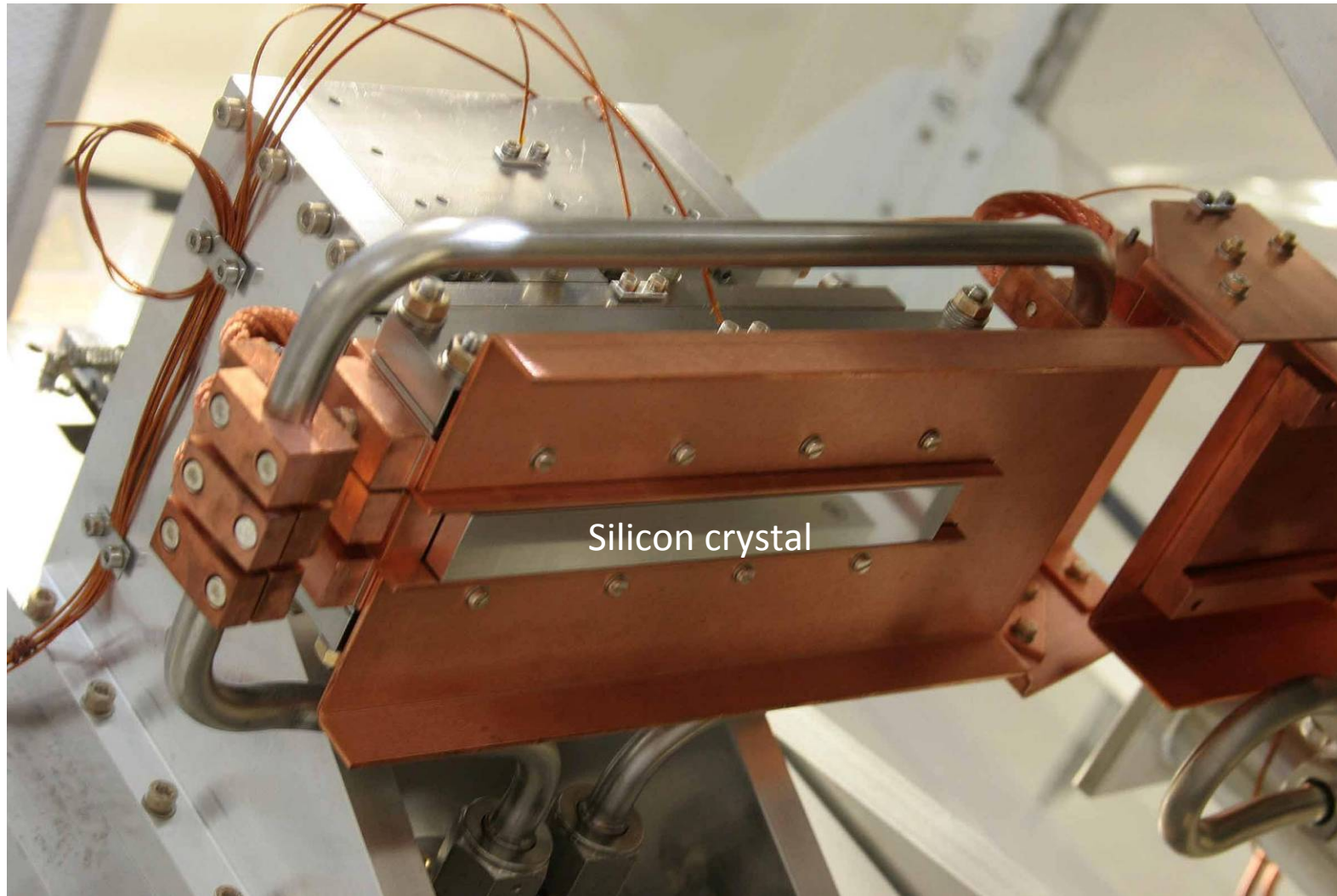


# + Cryogenic cooling of monochromator crystal

LN<sub>2</sub> cooling (Diamond)



Silicon crystal



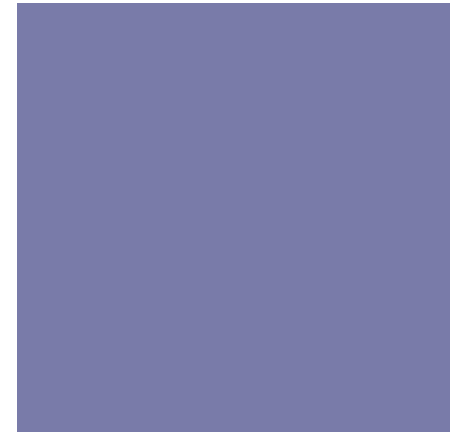
## Omitted topics

Electron analyzer

Crystal/multilayer analyzer

Ultra-fast detectors

Timing instruments



## Detectors

Ionization chamber, solid state detectors  
(Silicon, Germanium...)

## + Detectors used in XAS experiments

A. Ionization chamber (standard beam monitor in hard x-ray region)

a. Ambient gas pressure type

Control of absorbance: Mixing gas (N<sub>2</sub>-He, N<sub>2</sub>-Ar)

b. Pressurized gas type

Control of absorbance: Low vacuum, high vacuum

Beam monitor

F detector

c. Lytle detector

Fluorescence detection where energy resolution is not required

B. Solid state detectors (SSD) Energy resolution: 135-220 eV @5.9 keV

Silicon (Li) Pure Ge Upto 100 pixels; Oyanagi, NIM A513, 340 (2003).

C. Silicon drift diode (SDD) Energy resolution: 130 eV @5.9 keV

Upto five elements (?)

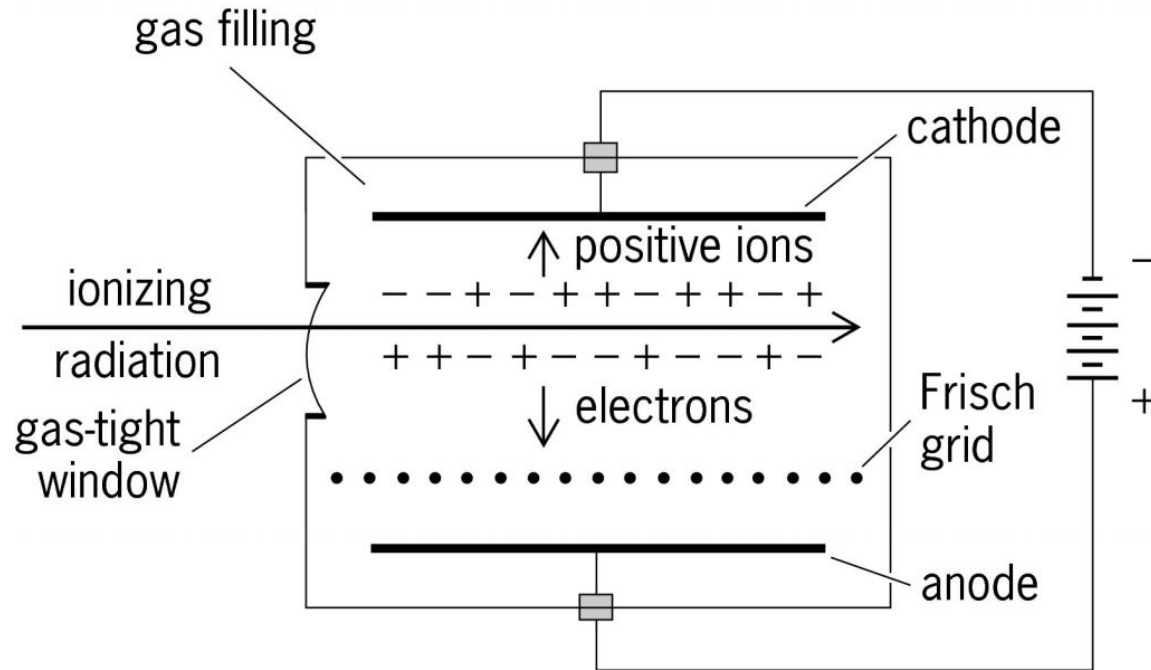
D. Si APD Fast response detector Energy resolution ≈26%

Kishimoto, RSI 63, 824 (1992)

E. Scintillation detector, NaI, plastic Energy resolution (NaI) ≈46%

F. Multilayer monochromator

# + Ionization chamber -Principle

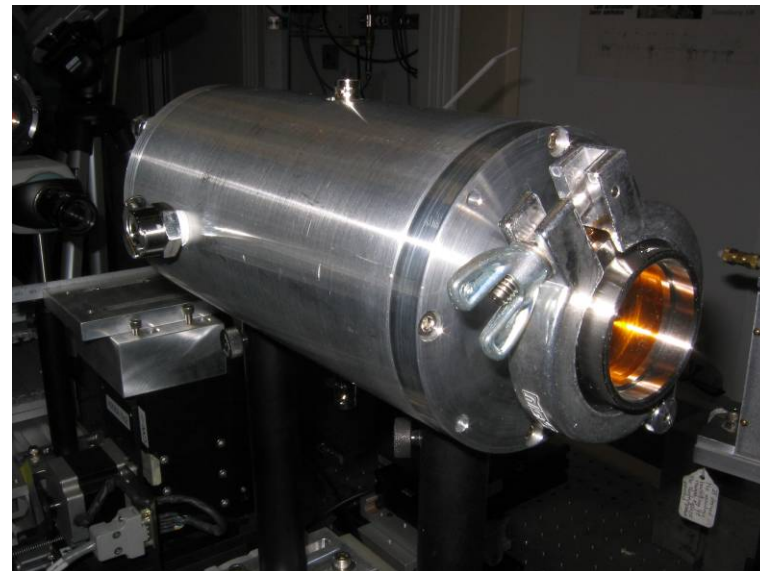


Note: frequent spike noise comes from a discharge  
Low voltage is recommended

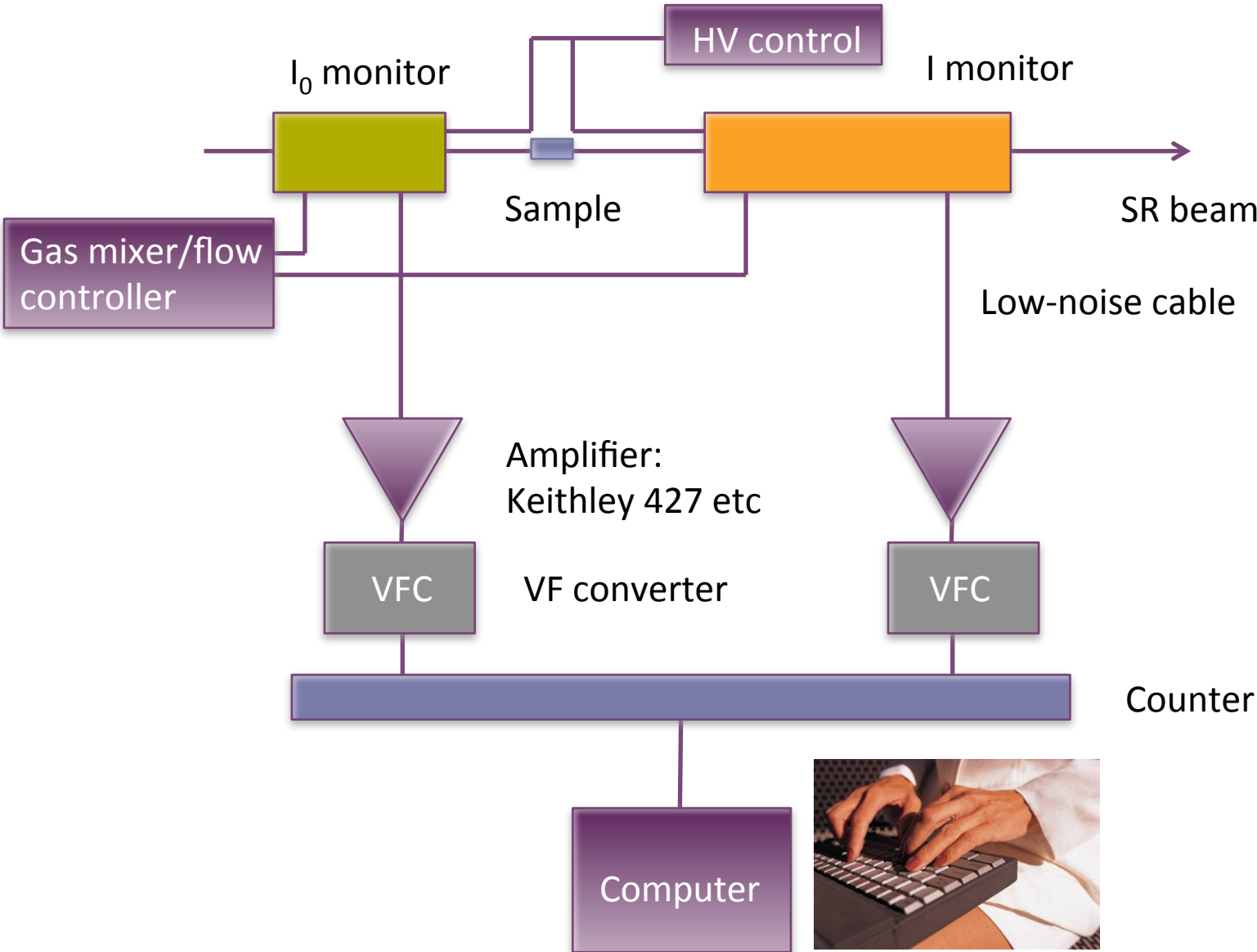
Two types of ionization chamber



@PF

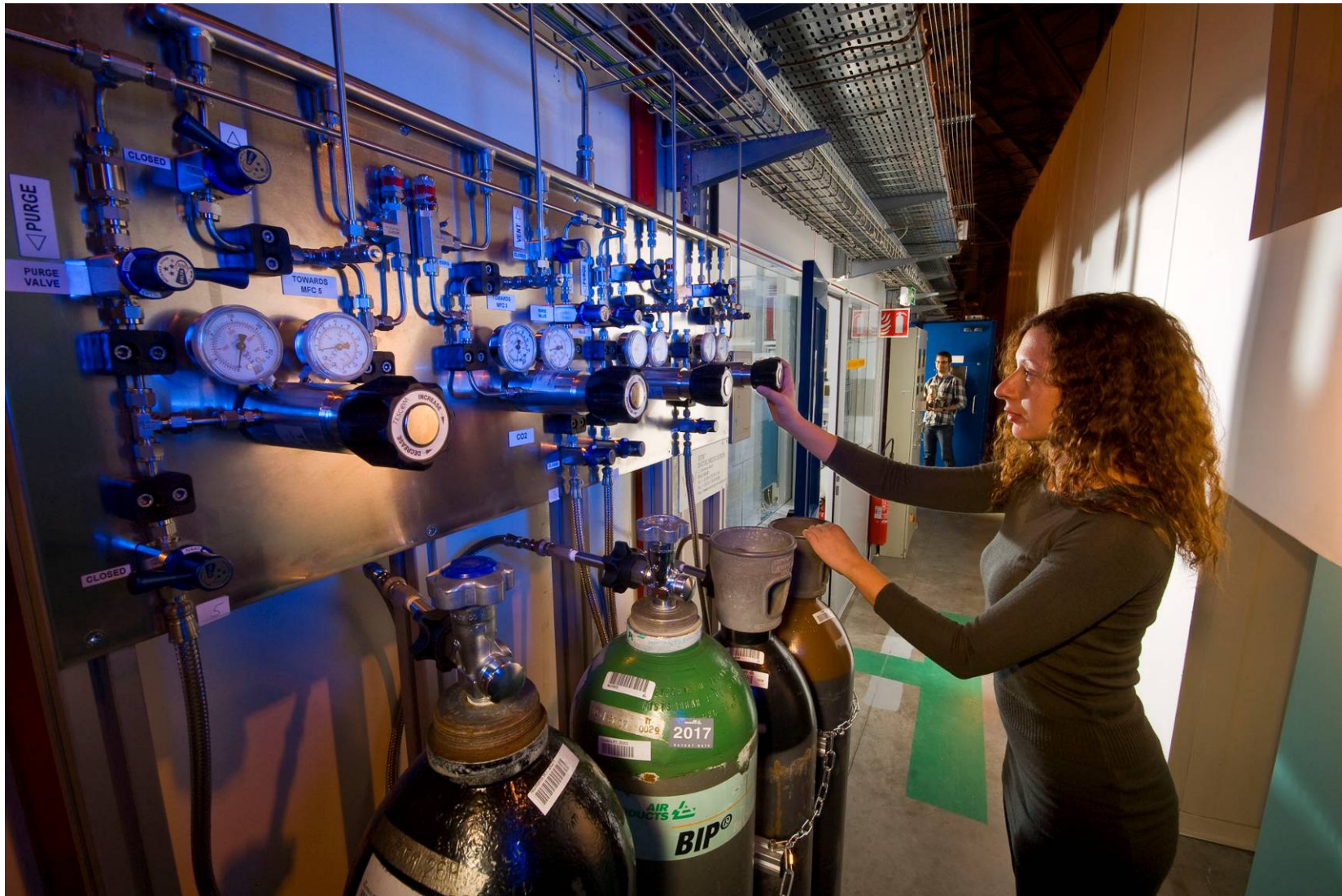


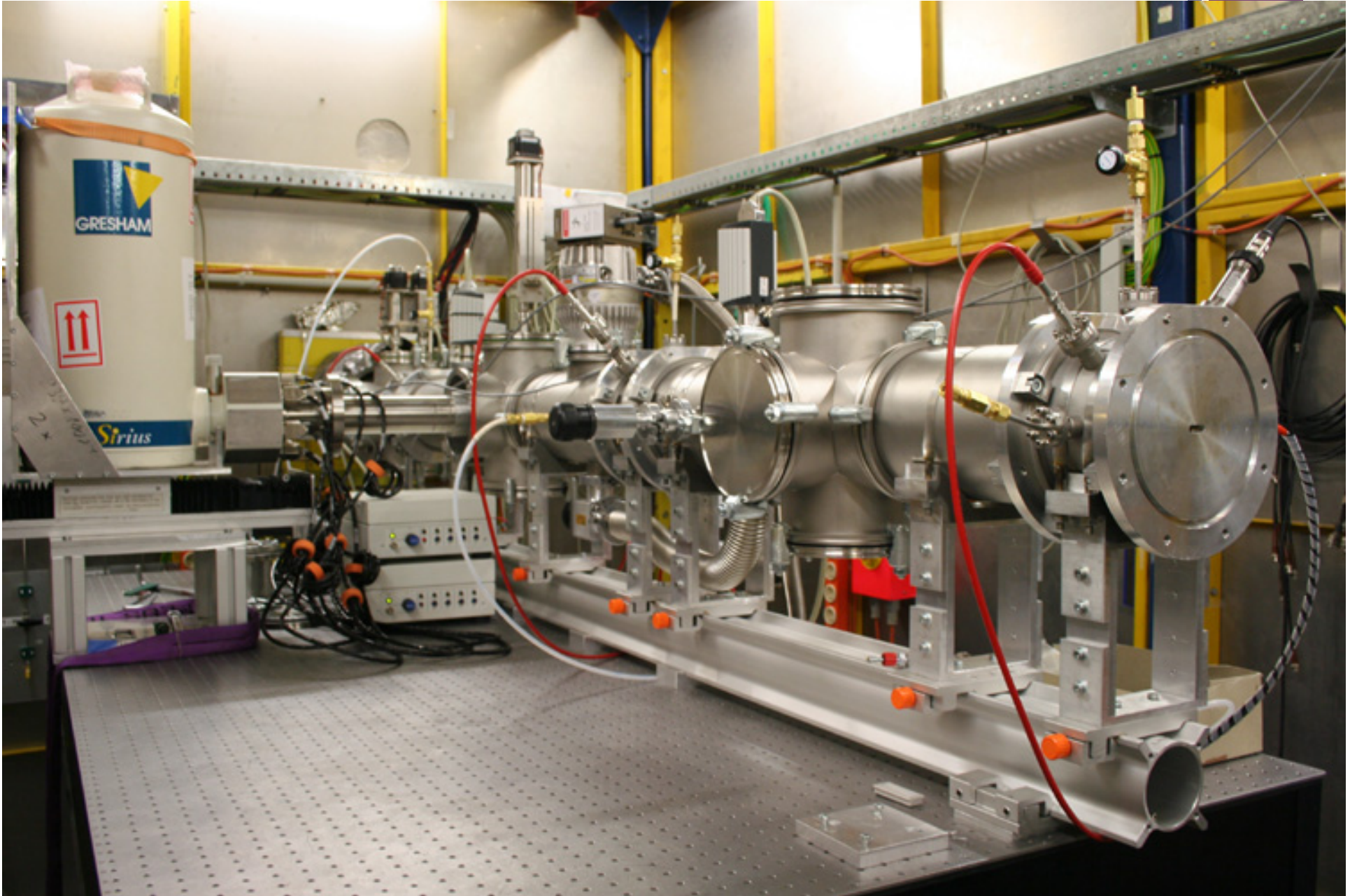
# + Conventional setup (Analog amplifier)



## + Ionization gas control

Controlled gas flow makes a stable signal output

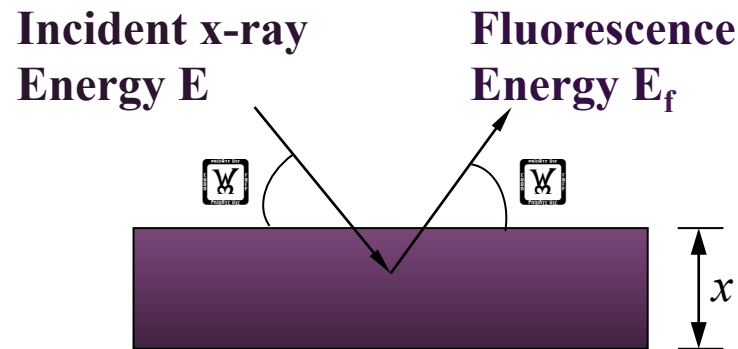




Pressurized ionization chamber setup at APS

## + Fluorescence intensity estimation

For x-rays incident on a slab of sample with thickness of  $x$ :



The fluorescence intensity  $I_f(E)$  accepted by a detector with a solid angle of  $\Omega/4\pi$  is:

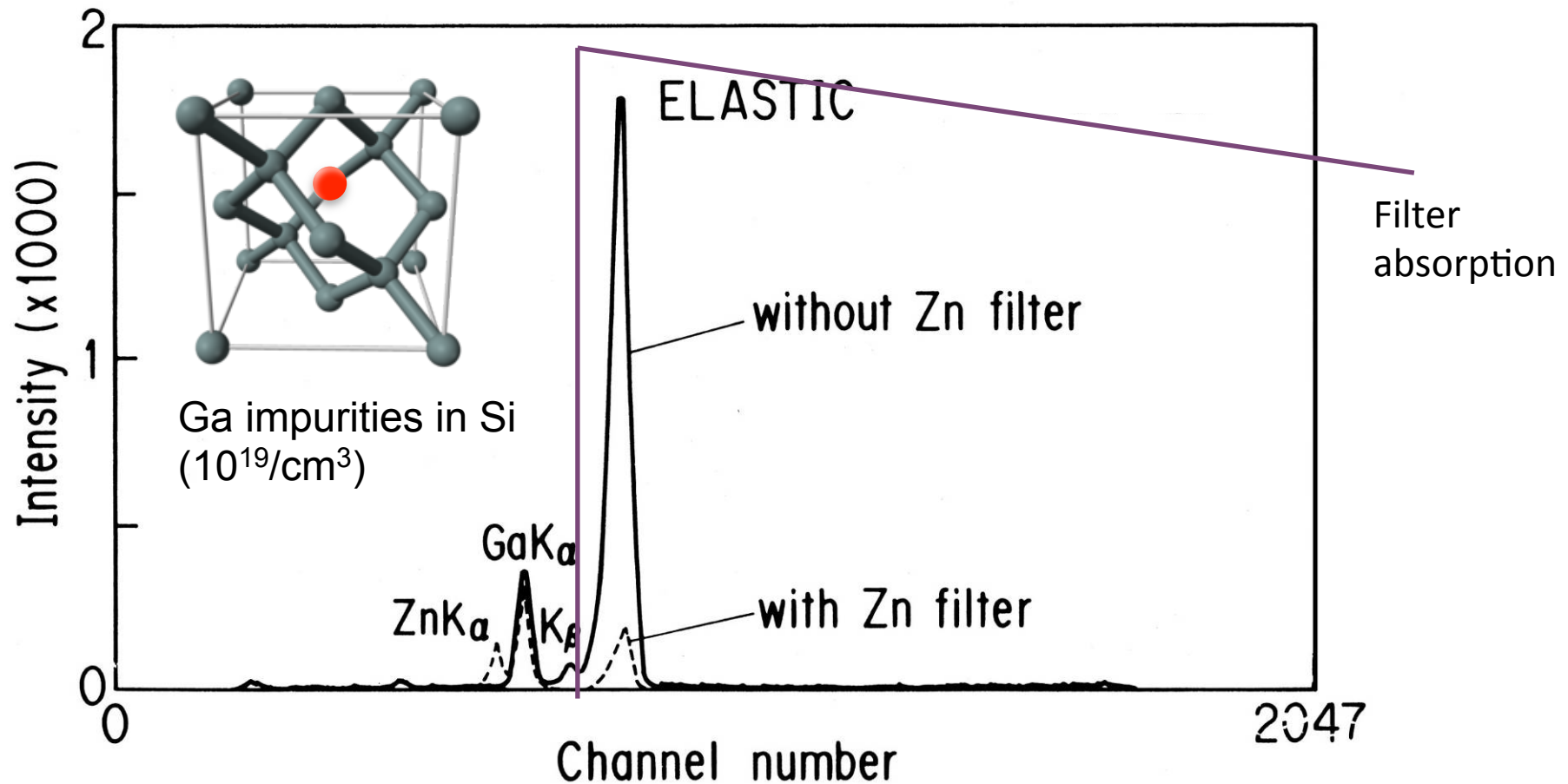
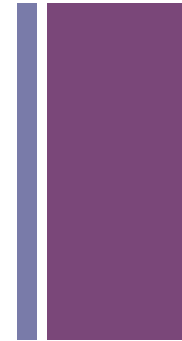
$$I_f(E) = I_0 \left( \frac{\Omega}{4\pi} \right) \epsilon \mu_{se}(E) / \sin \Theta \frac{1 - \exp[-(\mu(E) / \sin \Theta + \mu(E_f) / \sin \Phi)x]}{\mu(E) / \sin \Theta + \mu(E_f) / \sin \Phi} \quad (1)$$

$I_f(E) \approx I_0 \times 8.8 \times 10^{-4} \times 0.012 \times 1 \times 10^{-5} I_0$ , lower than  $I_0$  by 5 orders.



## + Fluorescence detection technique (Z-1 filter)

With a sacrifice of ½ intensity reduction, one order of magnitude of elastic x-ray background is removed by a fluorescence filter



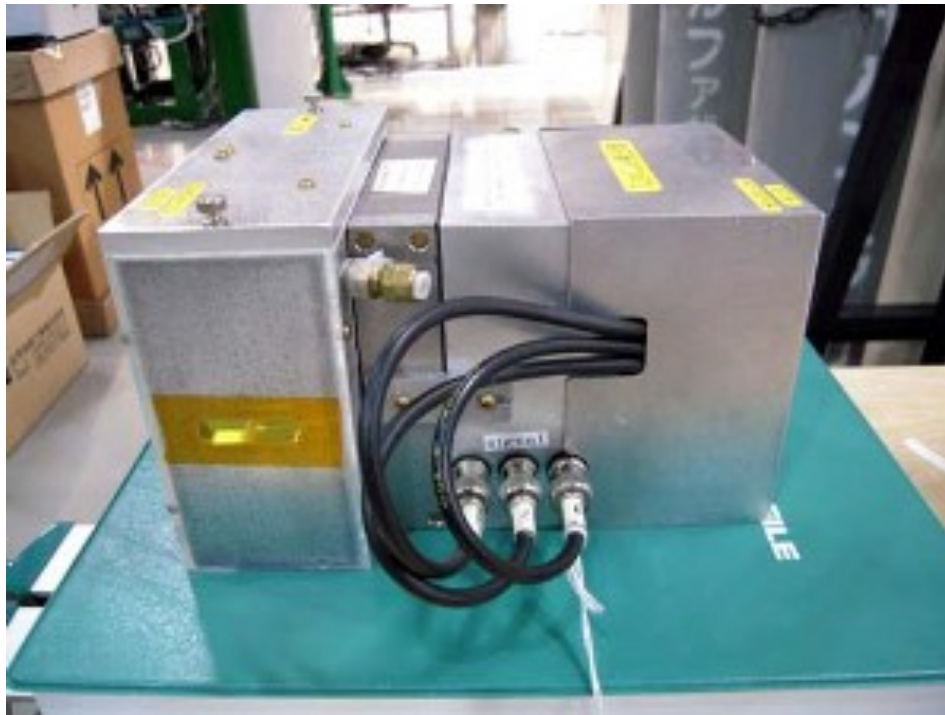
## + Lytle detector

Basically ionization chamber

Soller slit assembly to remove scattering and fluorescence background

[www.exafsc.com/](http://www.exafsc.com/)

@SagaLS



Note: easy-to-use and low-cost fluorescence detector

Note: never use in multi fluorescence signal sample

@APS

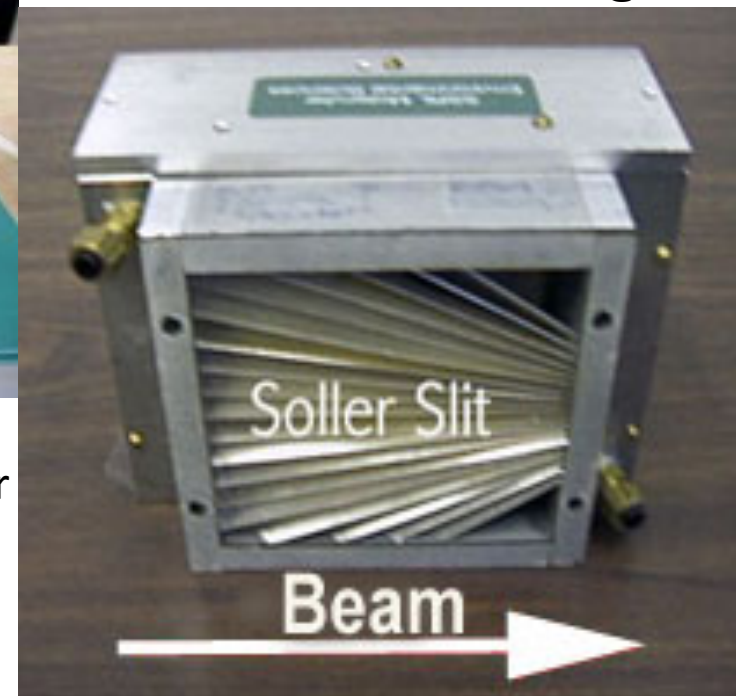


Figure 2. Soller Slit Position

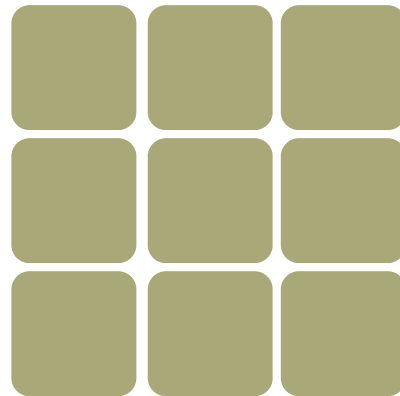
## + NaI array

For simple case, i.e., a single fluorescence line, energy resolving power becomes unimportant

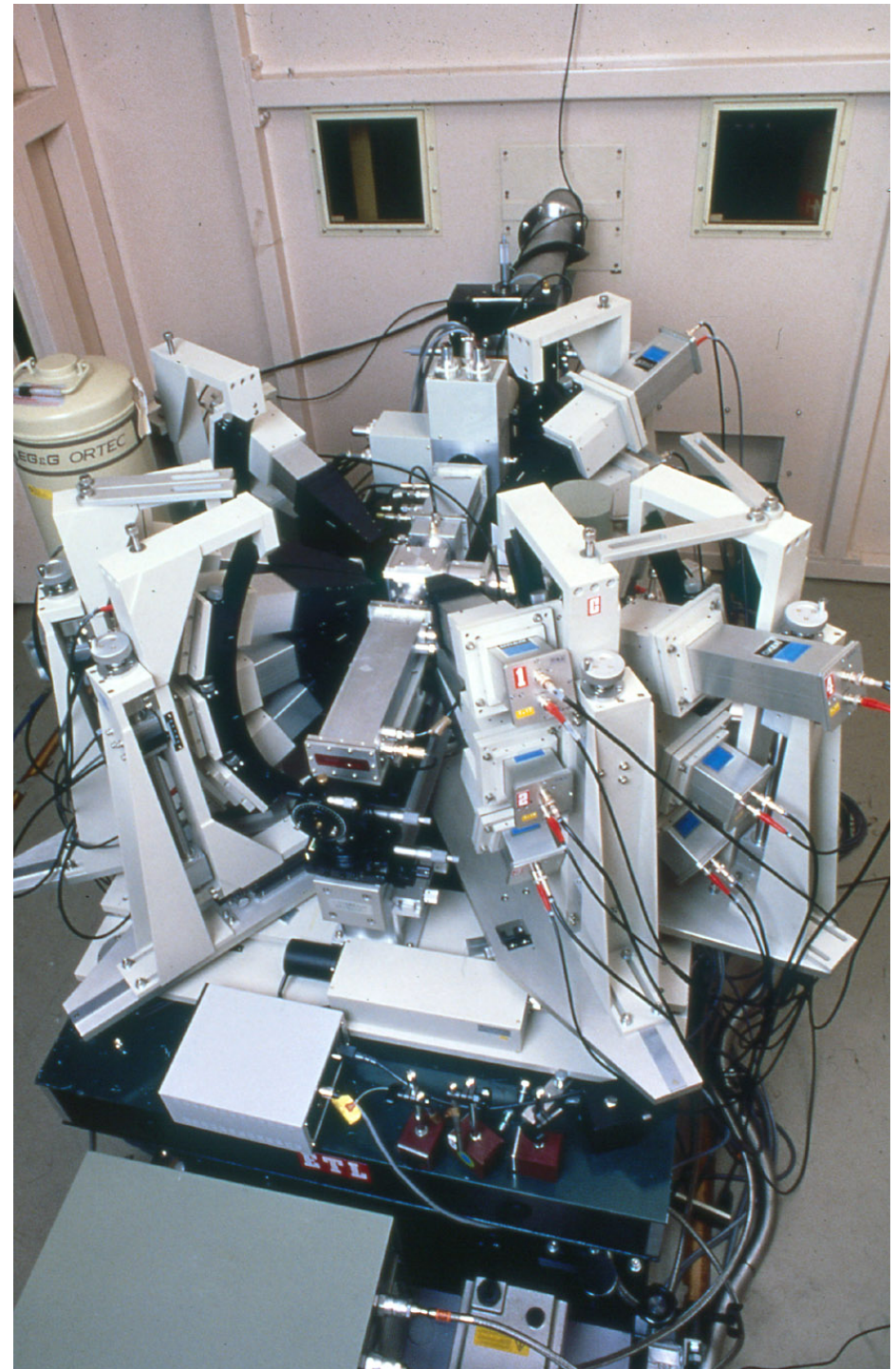
Lytle detector  
Si APD (DE $\approx$ 26%)  
NaI array (40-50%)

High coverage of solid angle but ...  
Low energy resolution

18% of 4p  
DE=41%E



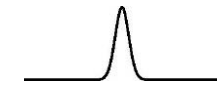
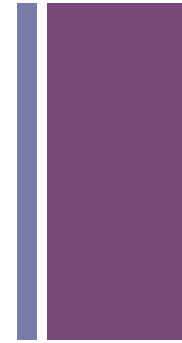
Focused beamline with a NaI array  
BL4C, 10C@PF



# + SSD (Solid State Detector) -a CMOS device for x-rays

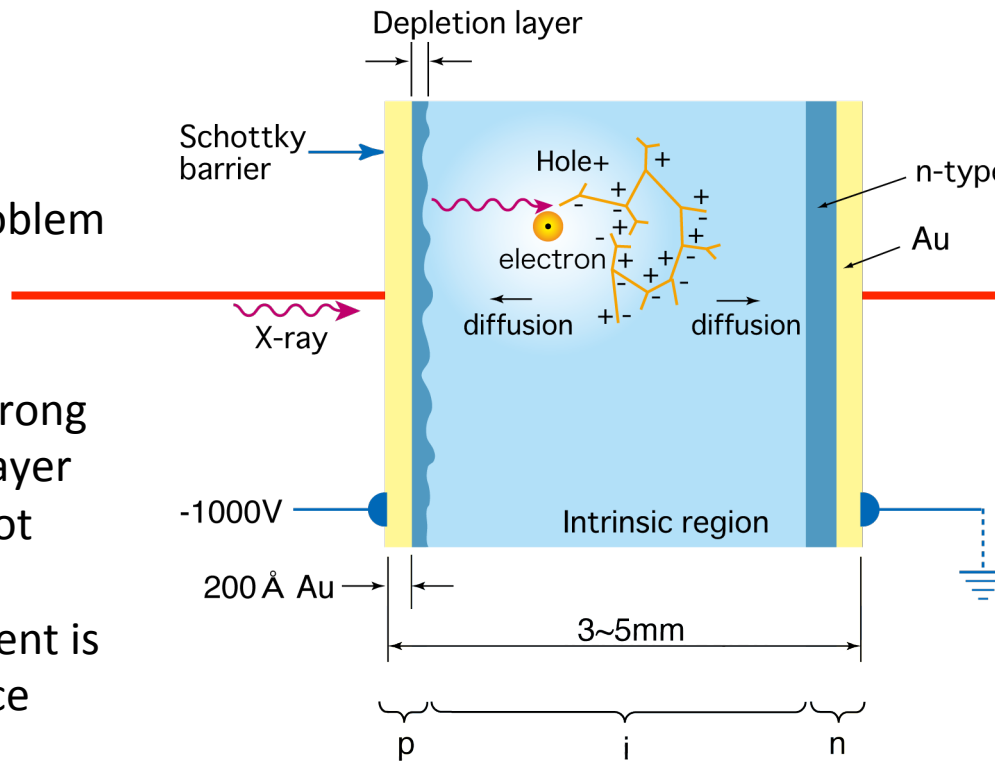
Each pixel acts as an independent SSD device

Signal (fluorescence) must be separated from elastic scattering  
And other backgrounds



Technical Problem

SiO<sub>2</sub> forms strong passivation layer but GeO<sub>2</sub> is not strong  
Leakage current is A noise source



**Signal (FY)**

**Background (Scattering, Fluorescence)**

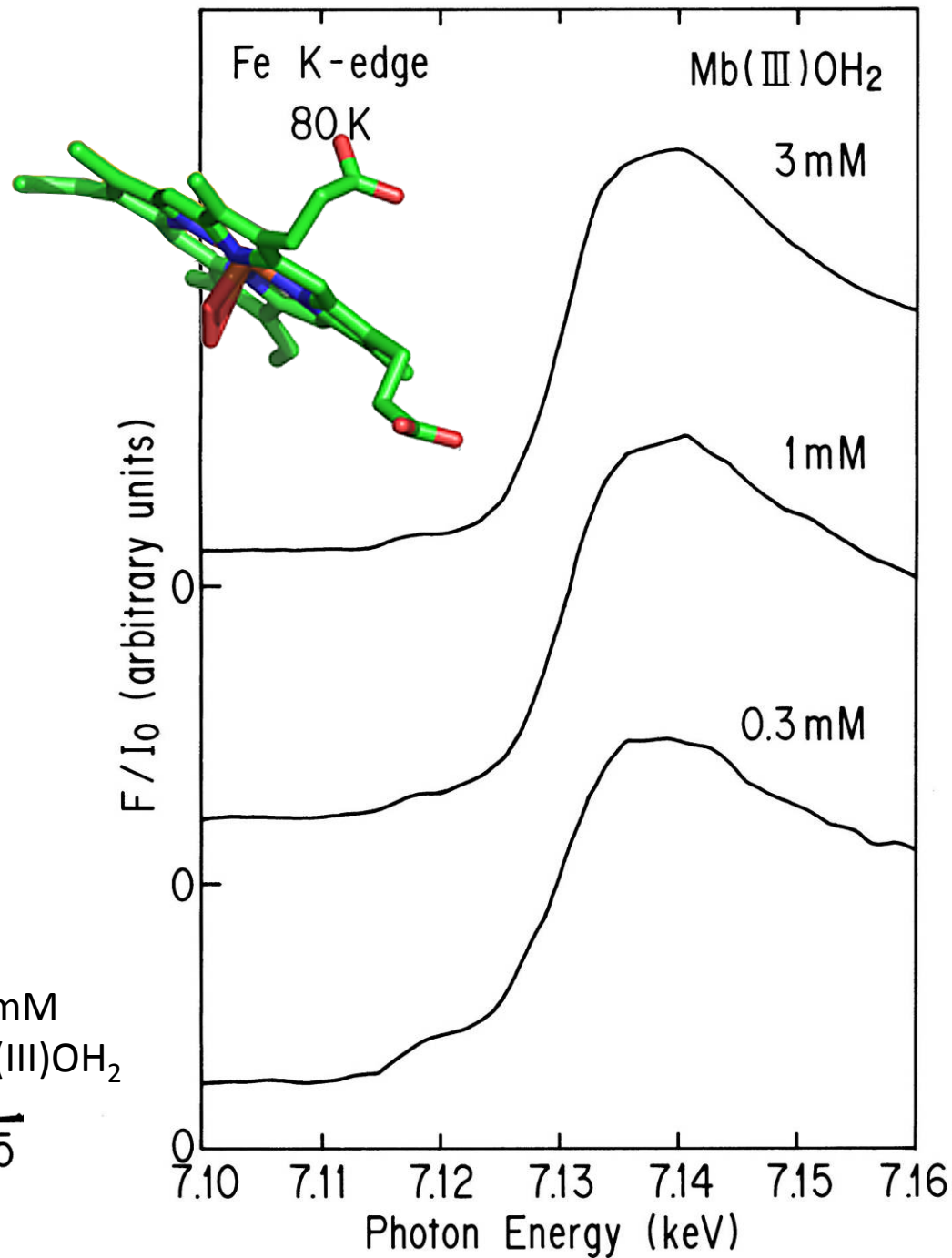
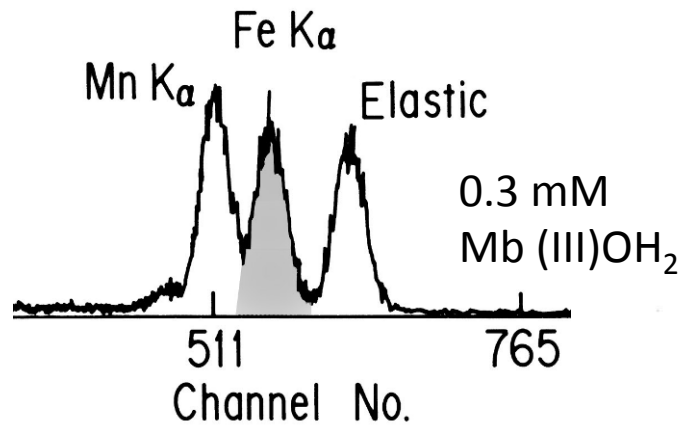


# + Fe K-XANES

Sample: Mb(III)OH<sub>2</sub>

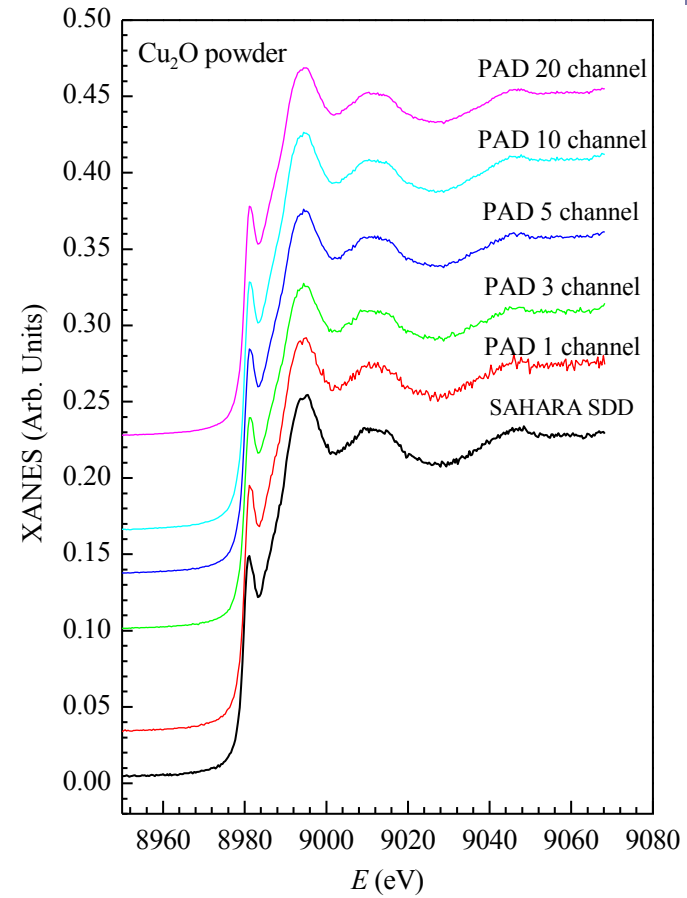
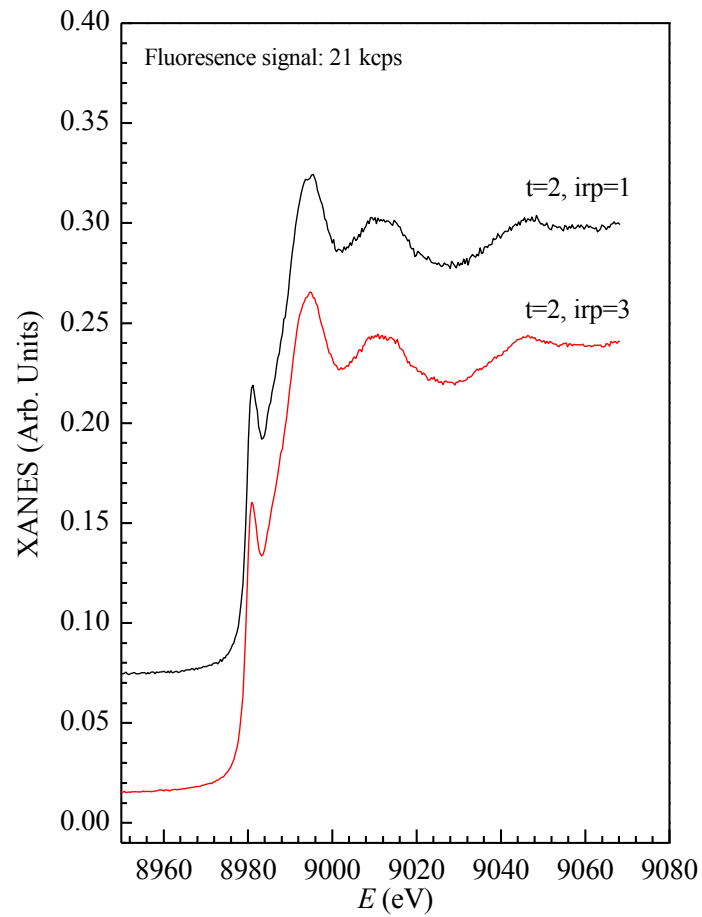
Signal: Fe fluorescence  
Background: Filter  
fluorescence plus  
elastic scattering

Statistics: Proportional  
to the square root of the  
accumulated number of  
photons



# + Statistics in fluorescence XAFS

- a. Repeating scans
- b. Segmented detection



# + Evolution of pixel array detector

## 1<sup>st</sup> Generation

5 mm x 5 mm  
100 pixels  
215 eV@5.9keV

No. 1 Spring-8 (Oyanagi)

09	19	29	39	49	59	69	79	89	99
08	18	28	38	48	58	68	78	88	98
07	17	27	37	47	57	67	77	87	97
06	16	26	36	46	56	66	76	86	96
05	15	25	35	45	55	65	75	85	95
04	14	24	34	44	54	64	74	84	94
03	13	23	33	43	53	63	73	83	93
02	12	22	32	42	52	62	72	82	92
01	11	21	31	41	51	61	71	81	91
00	10	20	30	40	50	60	70	80	90

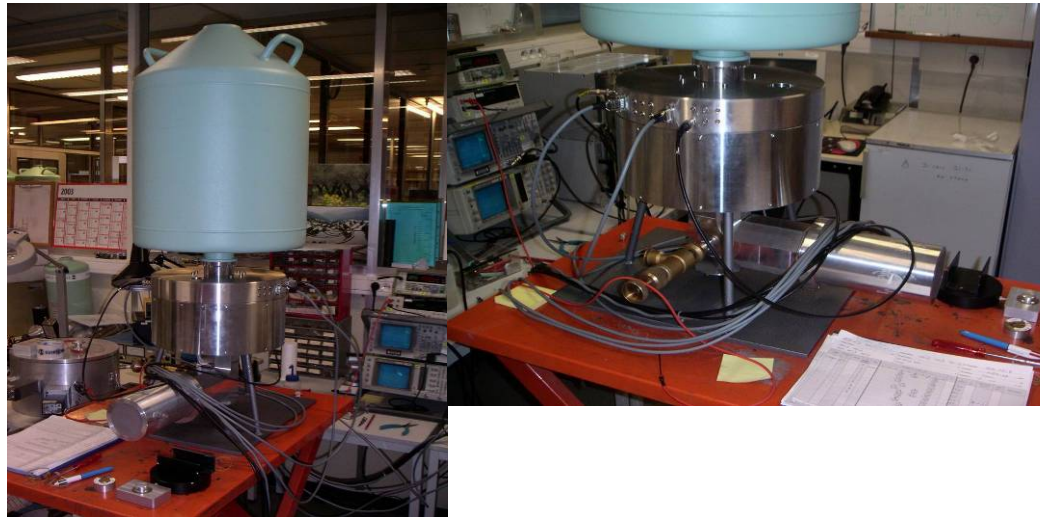
No. 2 Photon Factory (Oyanagi)

09	19	29	39	49	59	69	79	89	99
08	18	28	38	48	58	68	78	88	98
07	17	27	37	47	57	67	77	87	97
06	16	26	36	46	56	66	76	86	96
05	15	25	35	45	55	65	75	85	95
04	14	24	34	44	54	64	74	84	94
03	13	23	33	43	53	63	73	83	93
02	12	22	32	42	52	62	72	82	92
01	11	21	31	41	51	61	71	81	91
00	10	20	30	40	50	60	70	80	90

## 2<sup>nd</sup> Generation

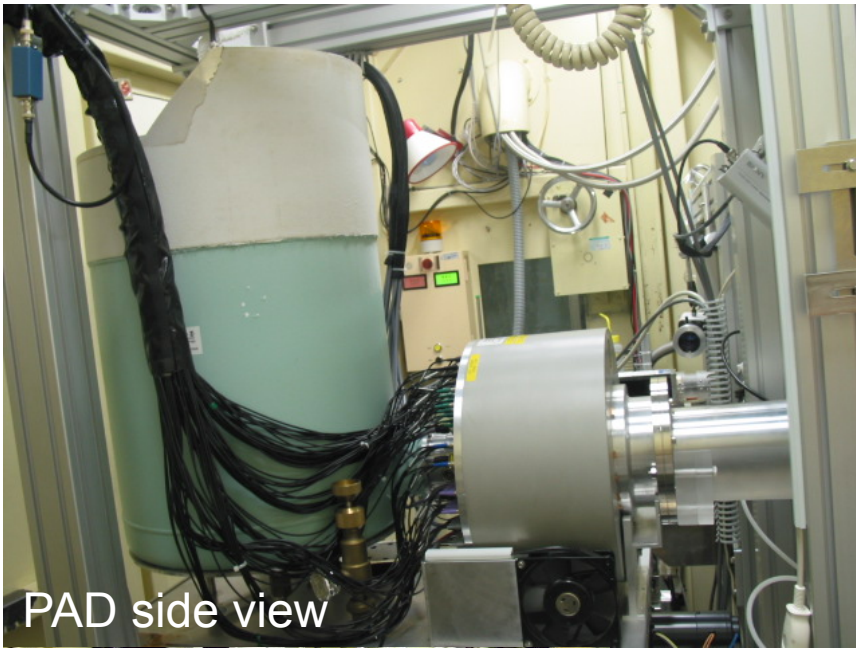
5 mm x 5 mm  
36 pixels  
165 eV@5.9keV

No. 3 Australian Beamline at PF (Foran et al.)



## 3<sup>rd</sup> Generation

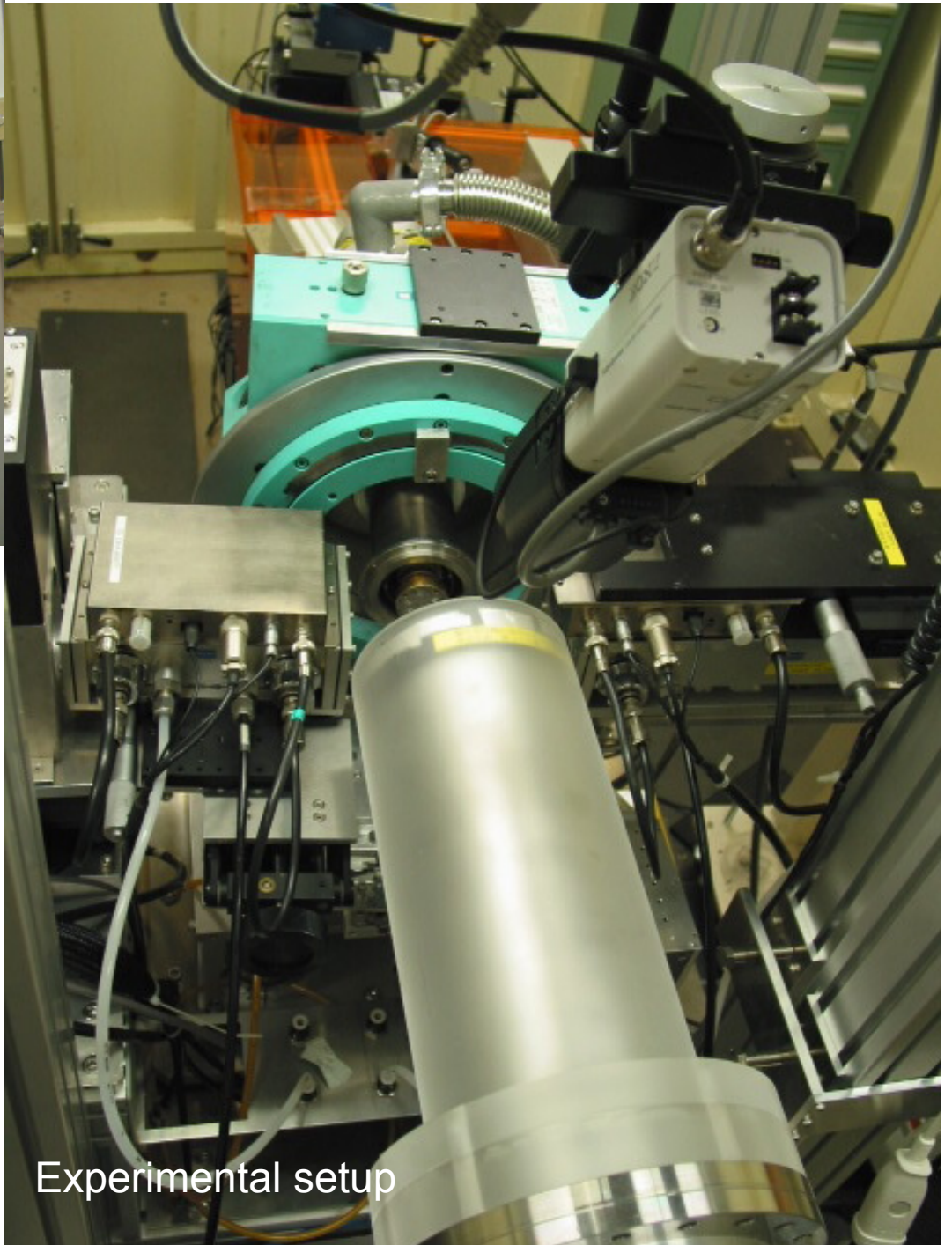
Now in operation in Australian light source



PAD side view



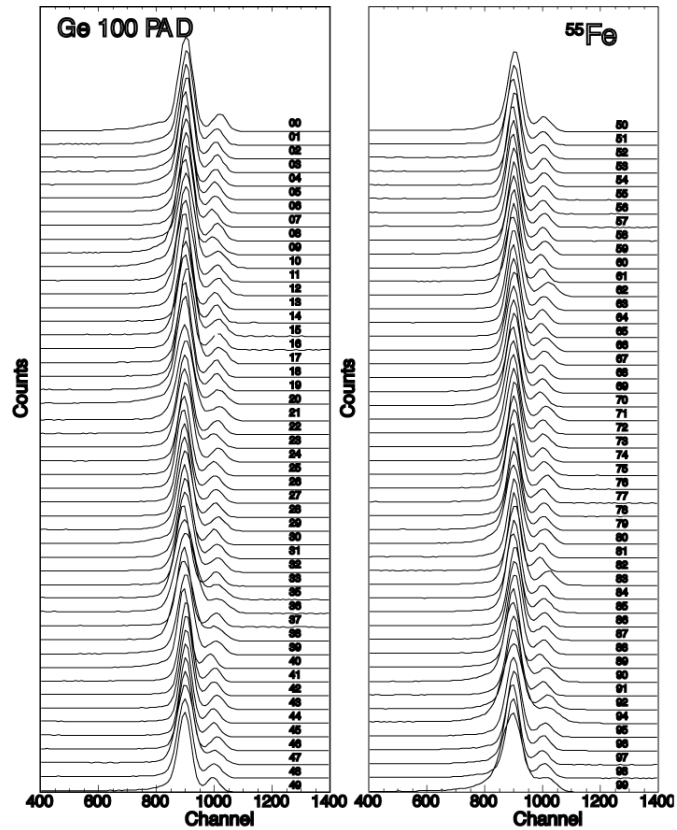
PAD front view



Experimental setup

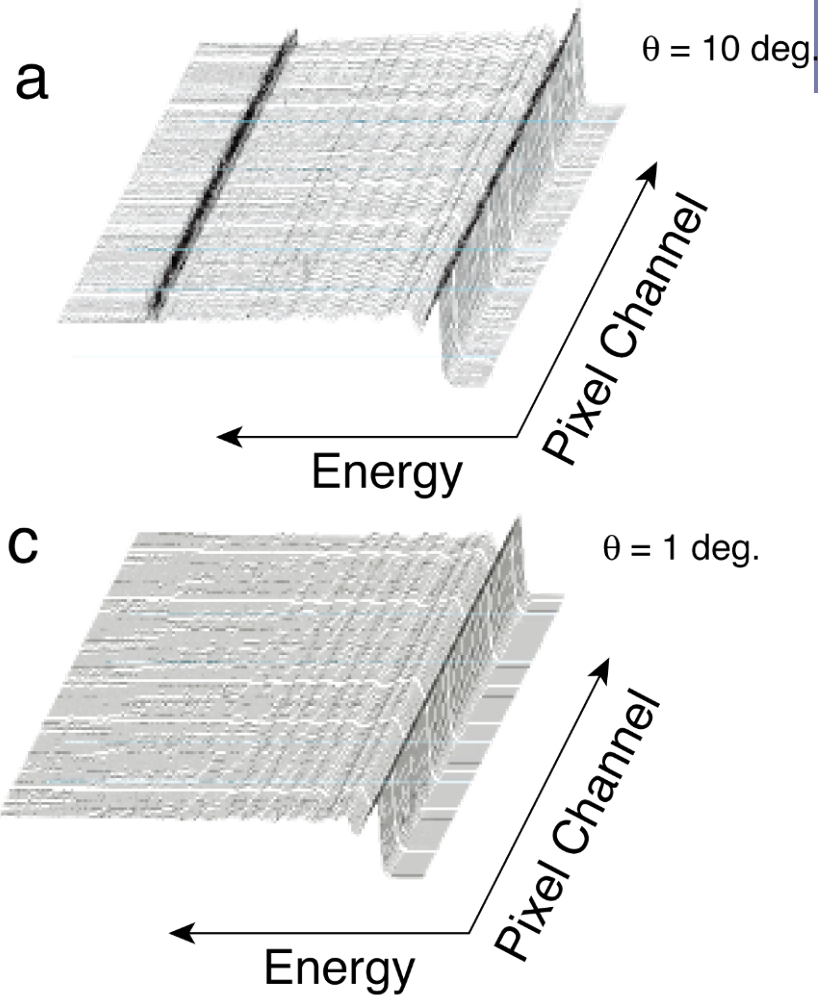


# + Advantage of PAD



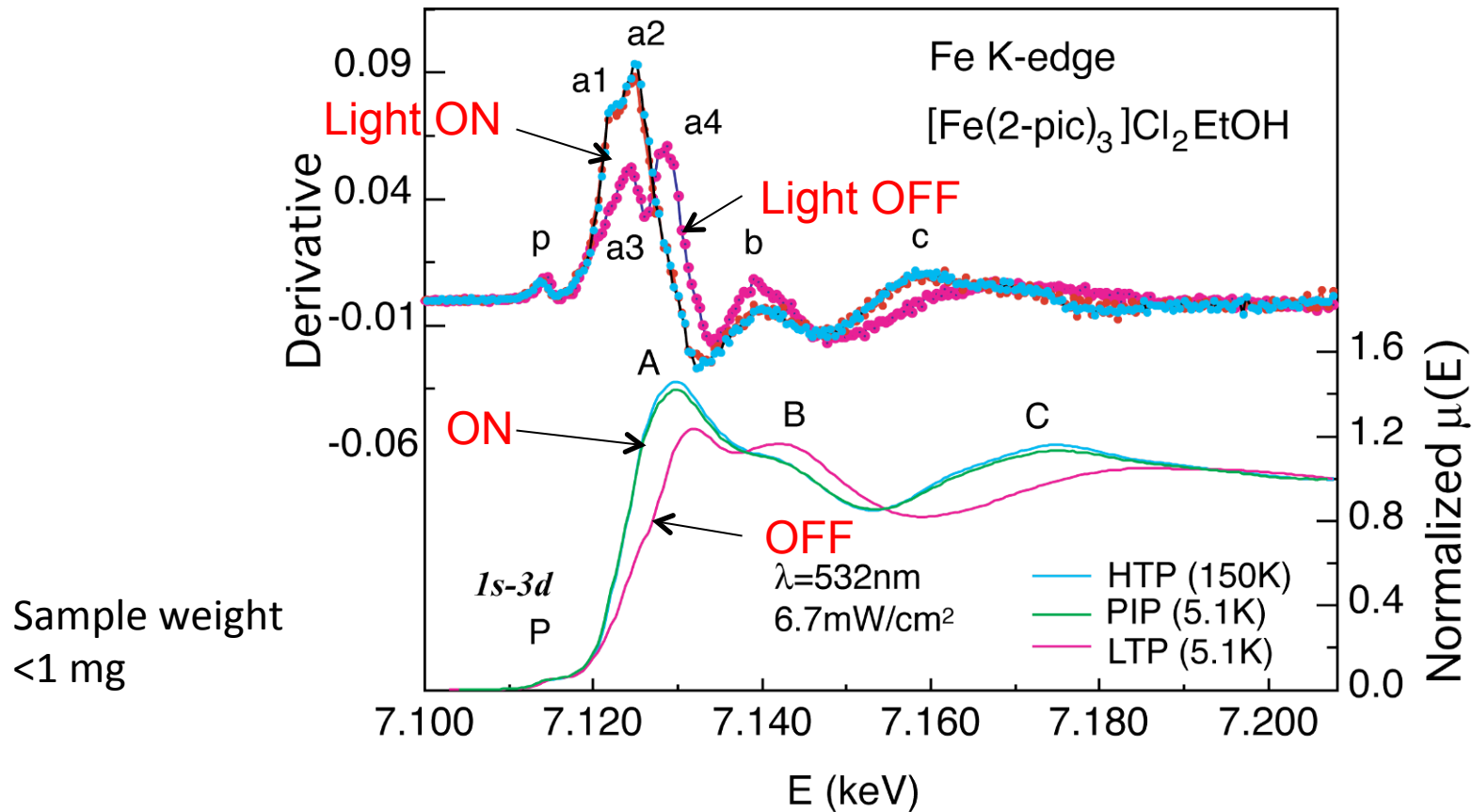
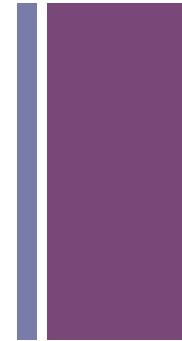
MCA output for 100 pixels

Real time fluorescence monitoring over a large segmented solid angle



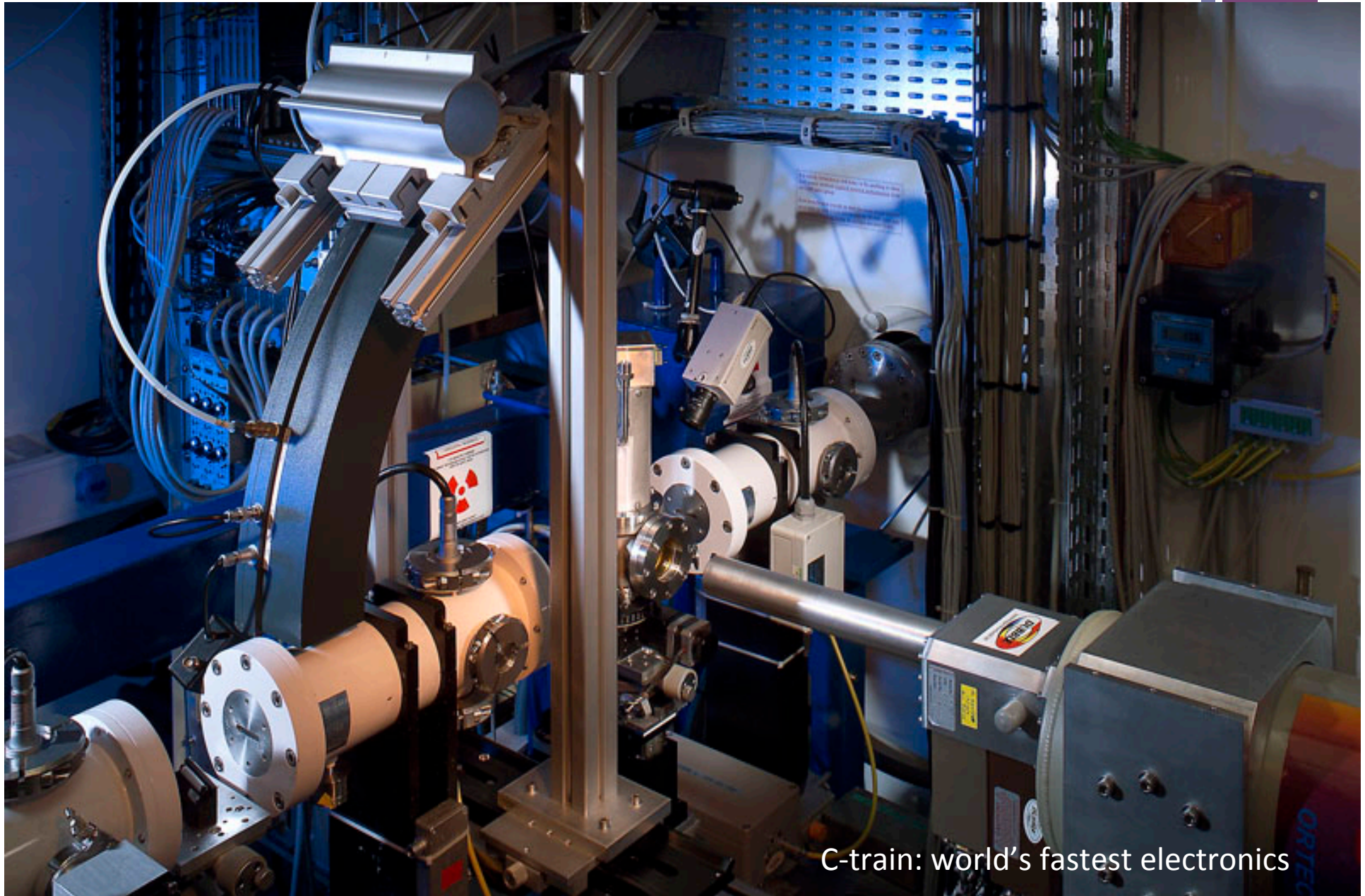
Glitches (scattering, standing wave, other elements) are completely removed.

+ Photo-induced spin crossover  
 –fluorescence detection by Ge PAD



Laser illumination changes Fe spin state from S=0 to S=2  
 No symmetry breaking!

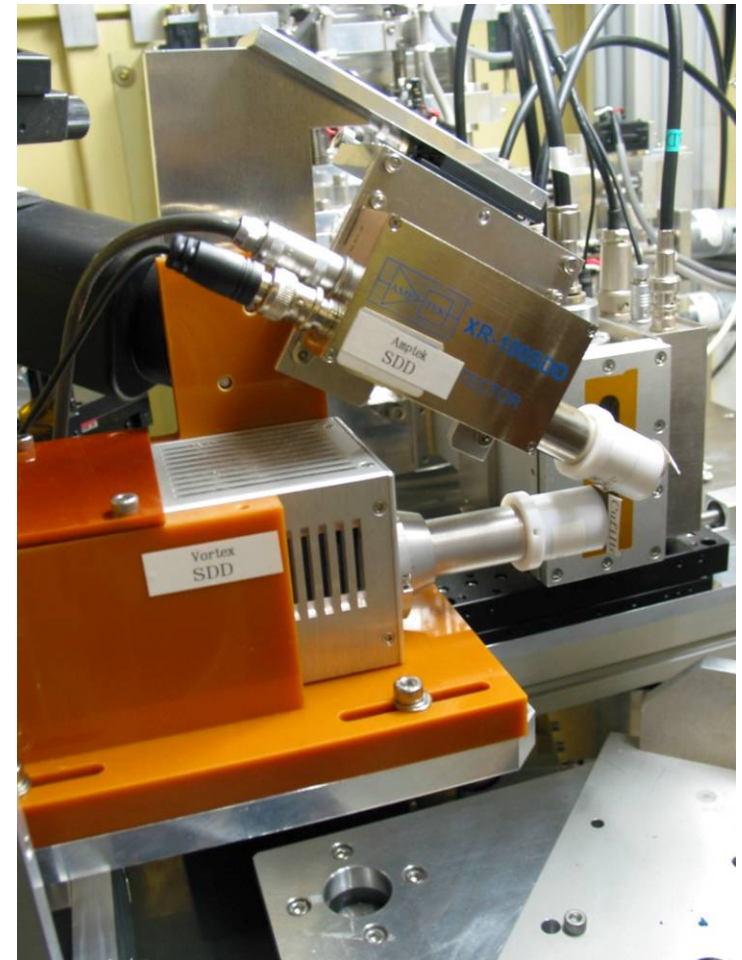
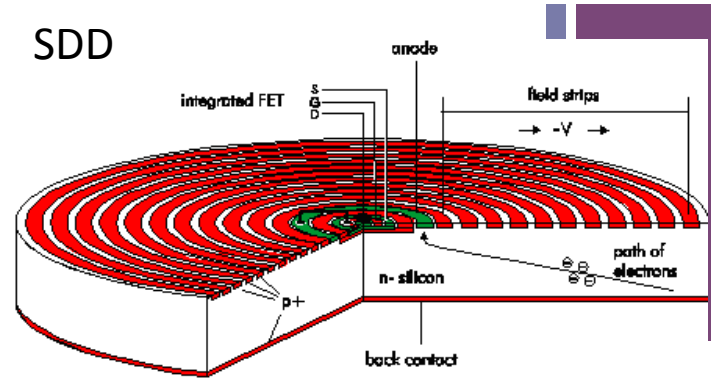
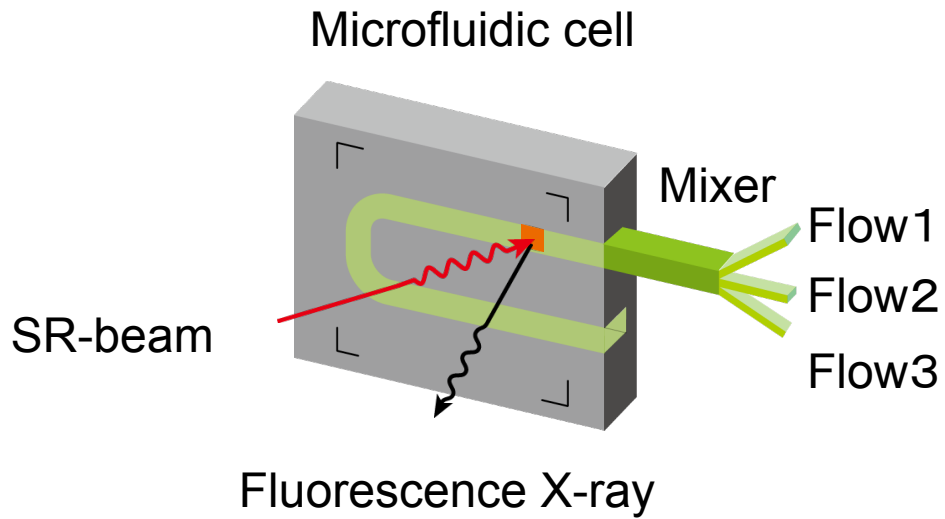
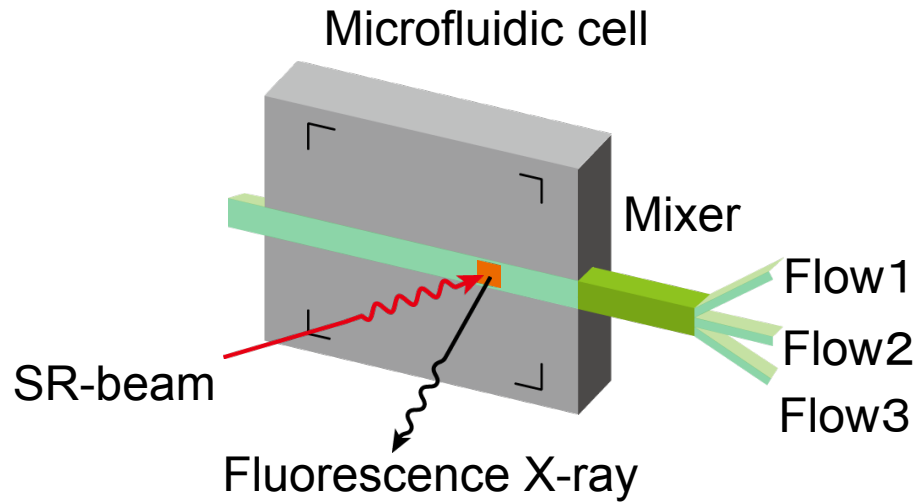
Oyanagi et al., *J. of Luminescence* 119, 361 (2006).

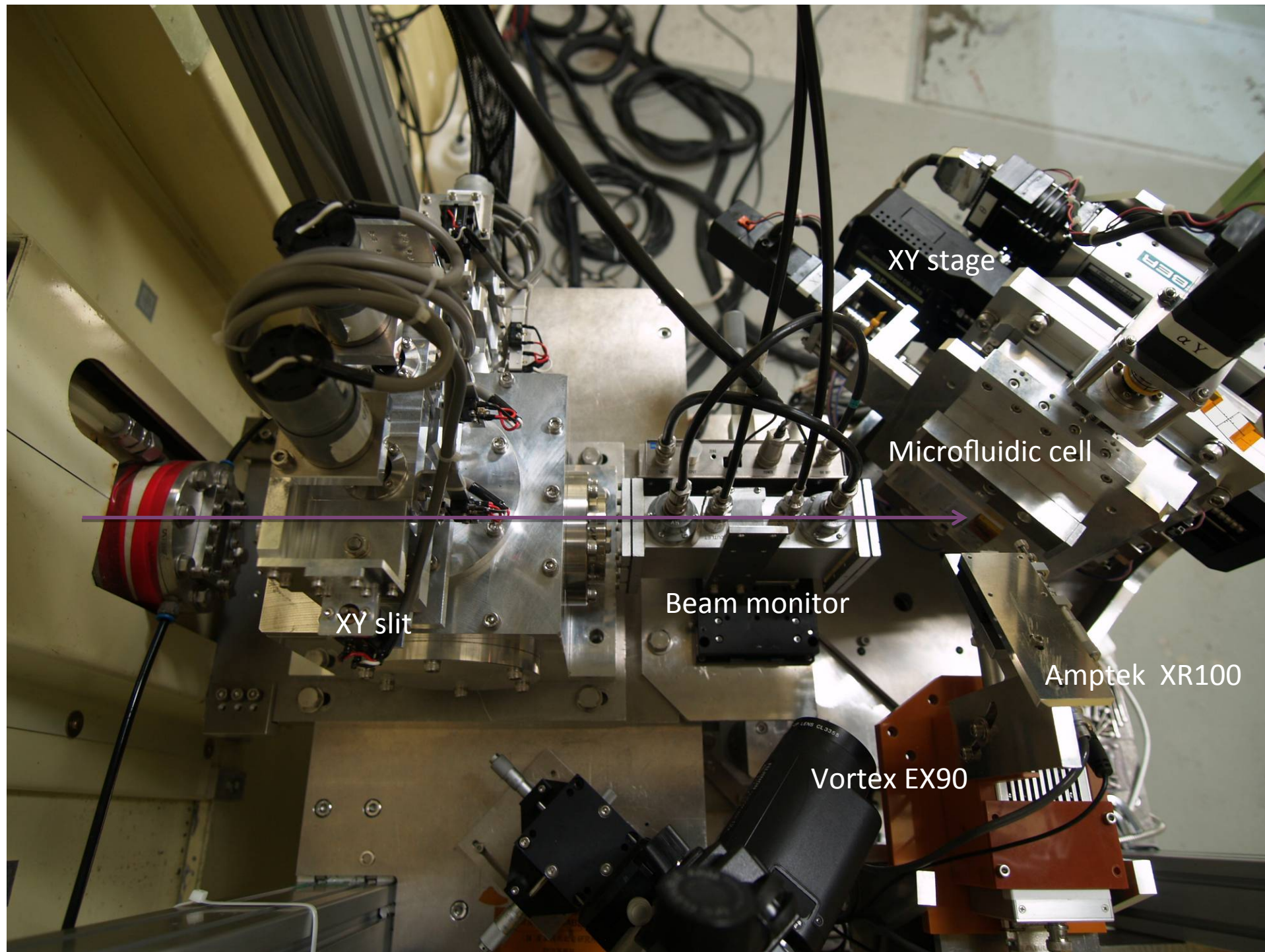


C-train: world's fastest electronics

Vacuum-tight ion chambers and a fast SSD @ESRF

+ XAFS experiment using a microfluidic cell





XY stage

Microfluidic cell

Beam monitor

XY slit

Amptek XR100

Vortex EX90



## Omitted topics

Energy dispersive EXAFS

Quick scan

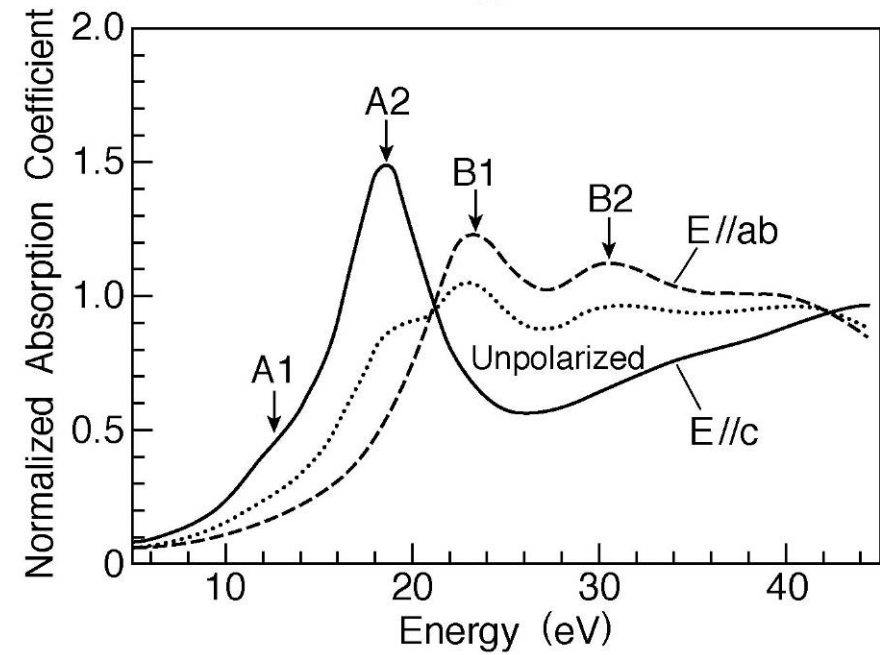
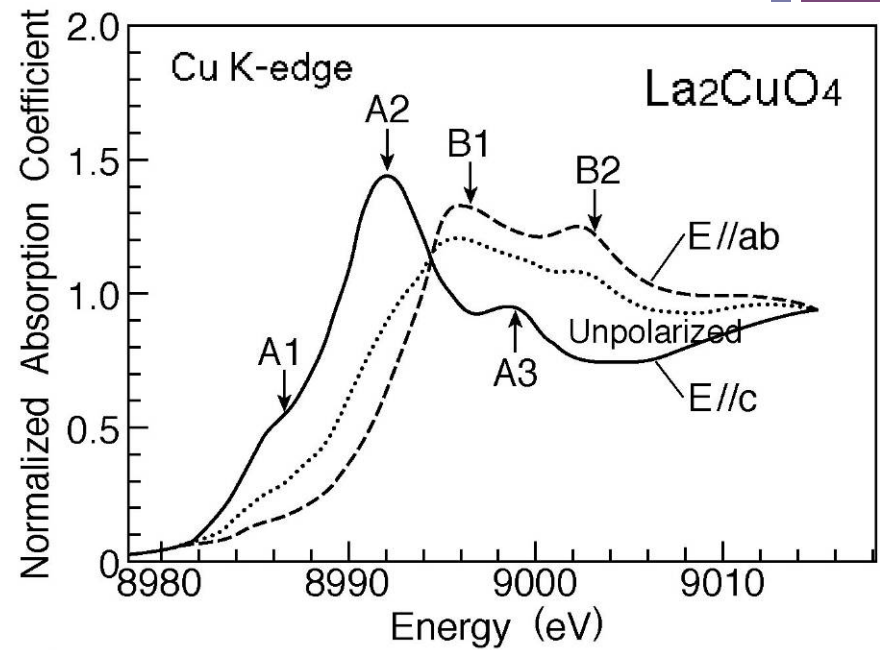
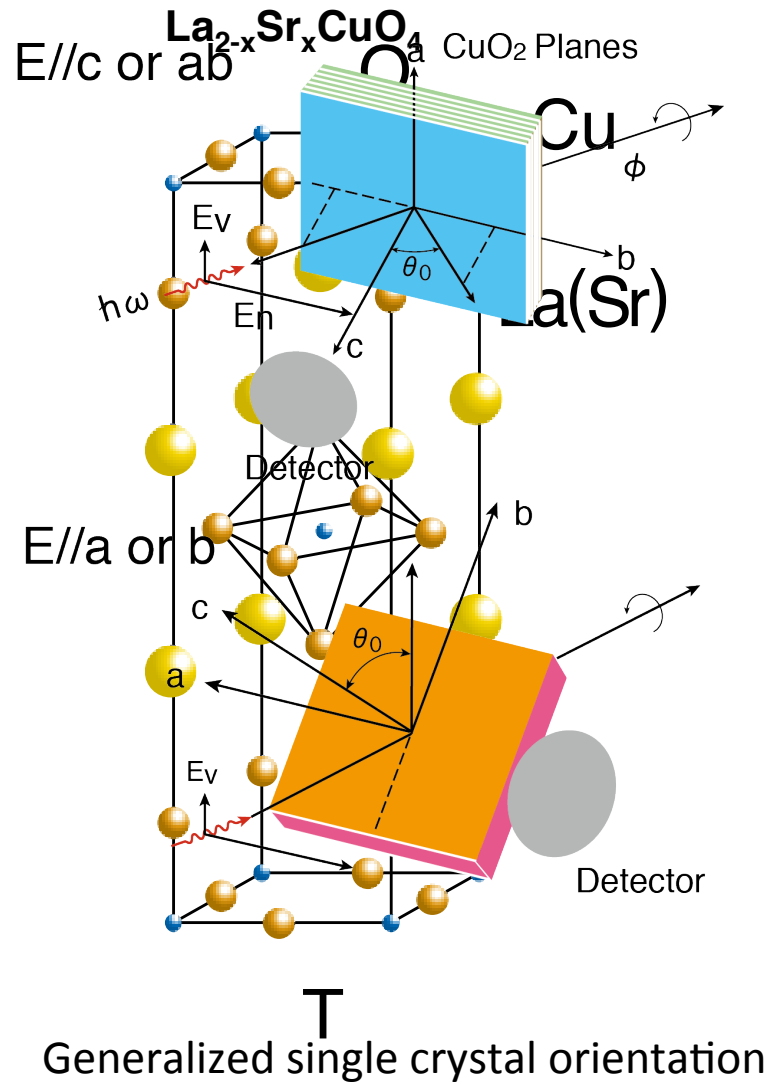
Pump & probe



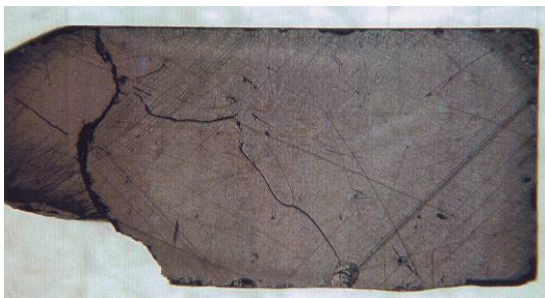
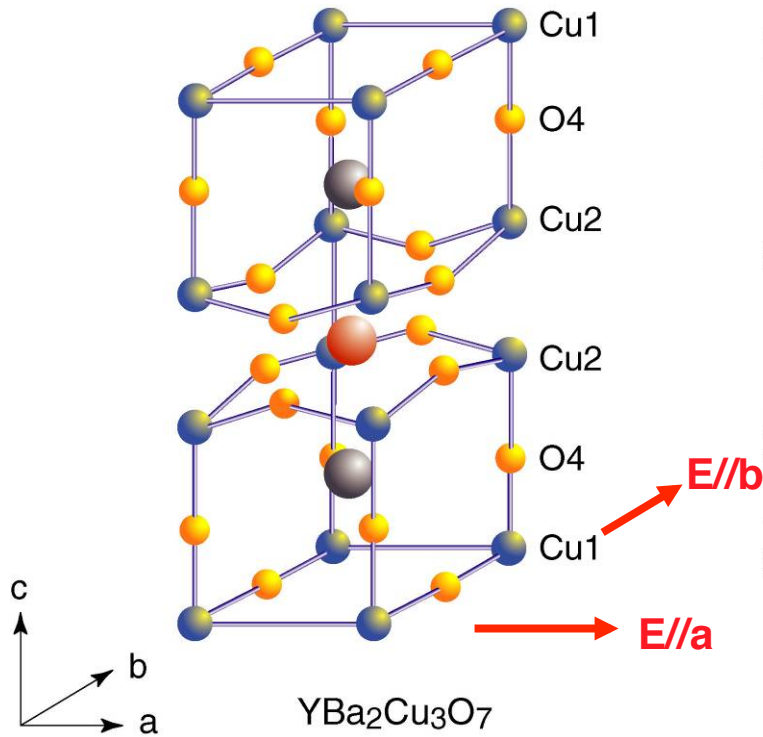
## Measurement modes geometry

Transmission and fluorescence

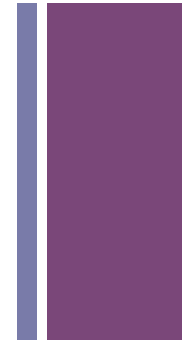
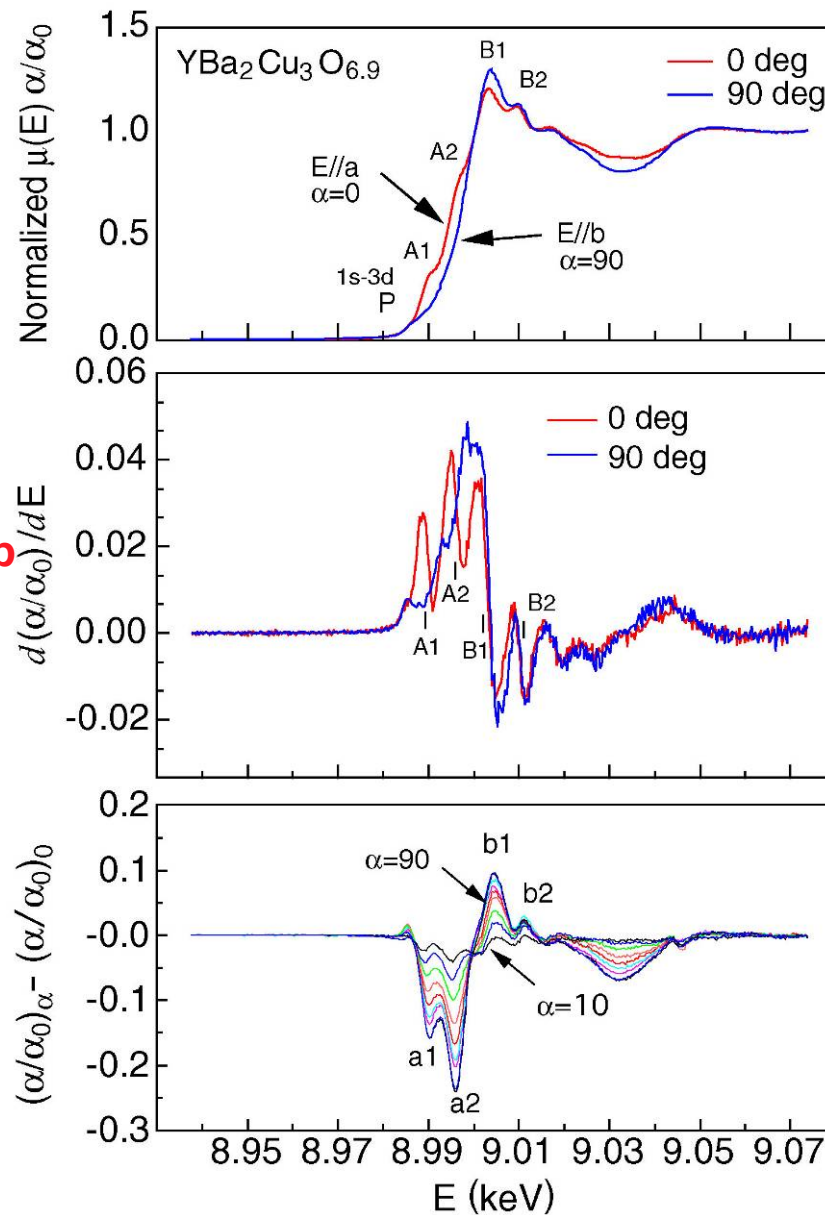
# + Geometries



# + In-plane anisotropy



High-quality YBa<sub>2</sub>Cu<sub>3</sub>O<sub>y</sub> crystal

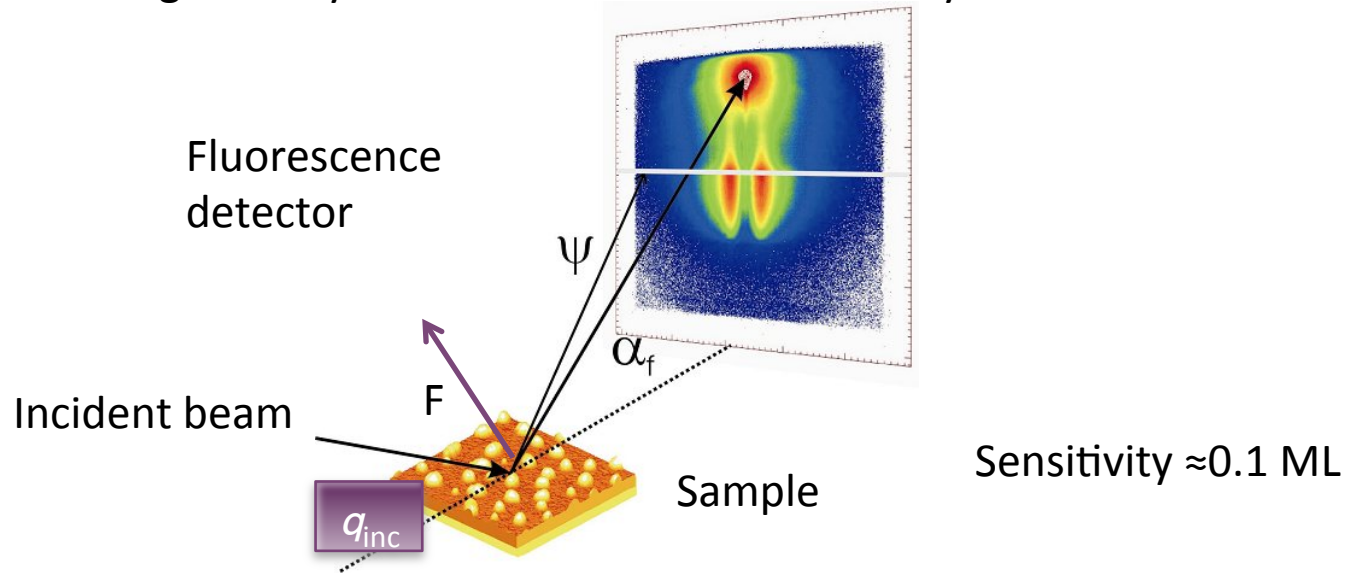




# + Grazing incidence geometry

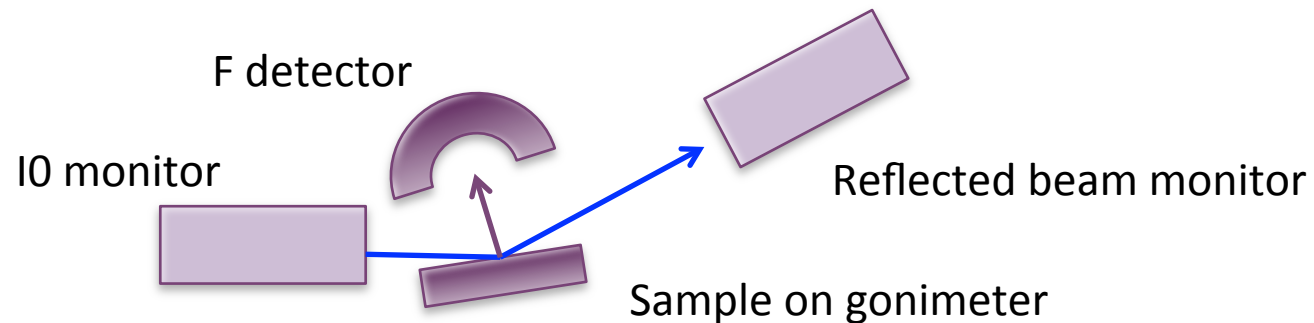
Surface-sensitive geometry

Surface scattered x-rays



In a total reflection regime,  $q_{inc} < q_c$

Selective excitation of surface with background reduction is possible  
Increasing surface sensitivity to 0.1 monolayer (ML) level



+ XSW (X-ray Standing Wave) set up  
Zegenhagen & Oyanagi @BL13/PF

Electrochemistry cell (GaAs substrate)

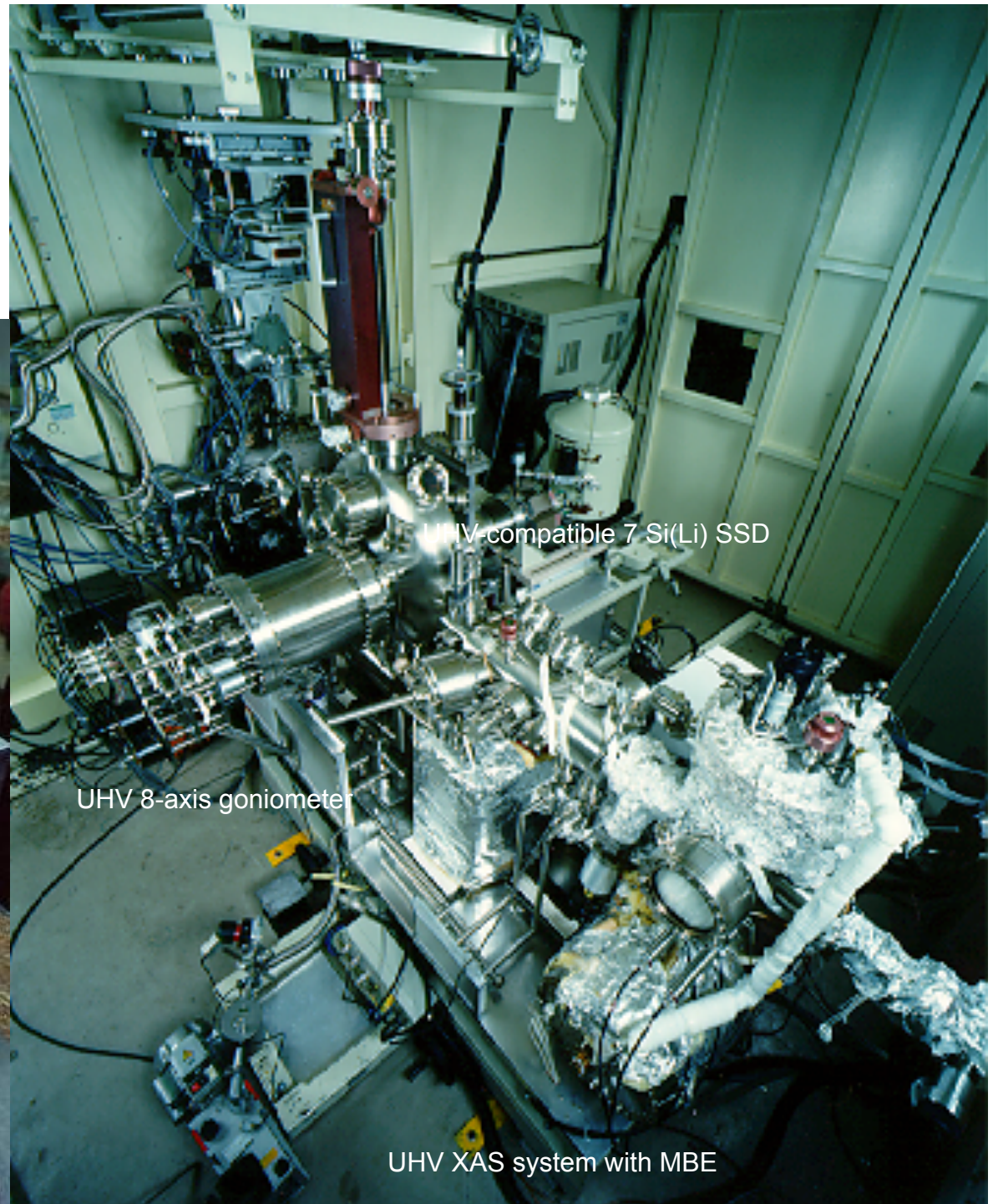


$i_0$  monitor ( $l=140$  mm,  $N_2$  gas)

ii (reflected beam) monitor  
( $l=280$  mm,  $N_2$  or  $N_2+Ar$  gas)

# + UHV fluorescence experiment

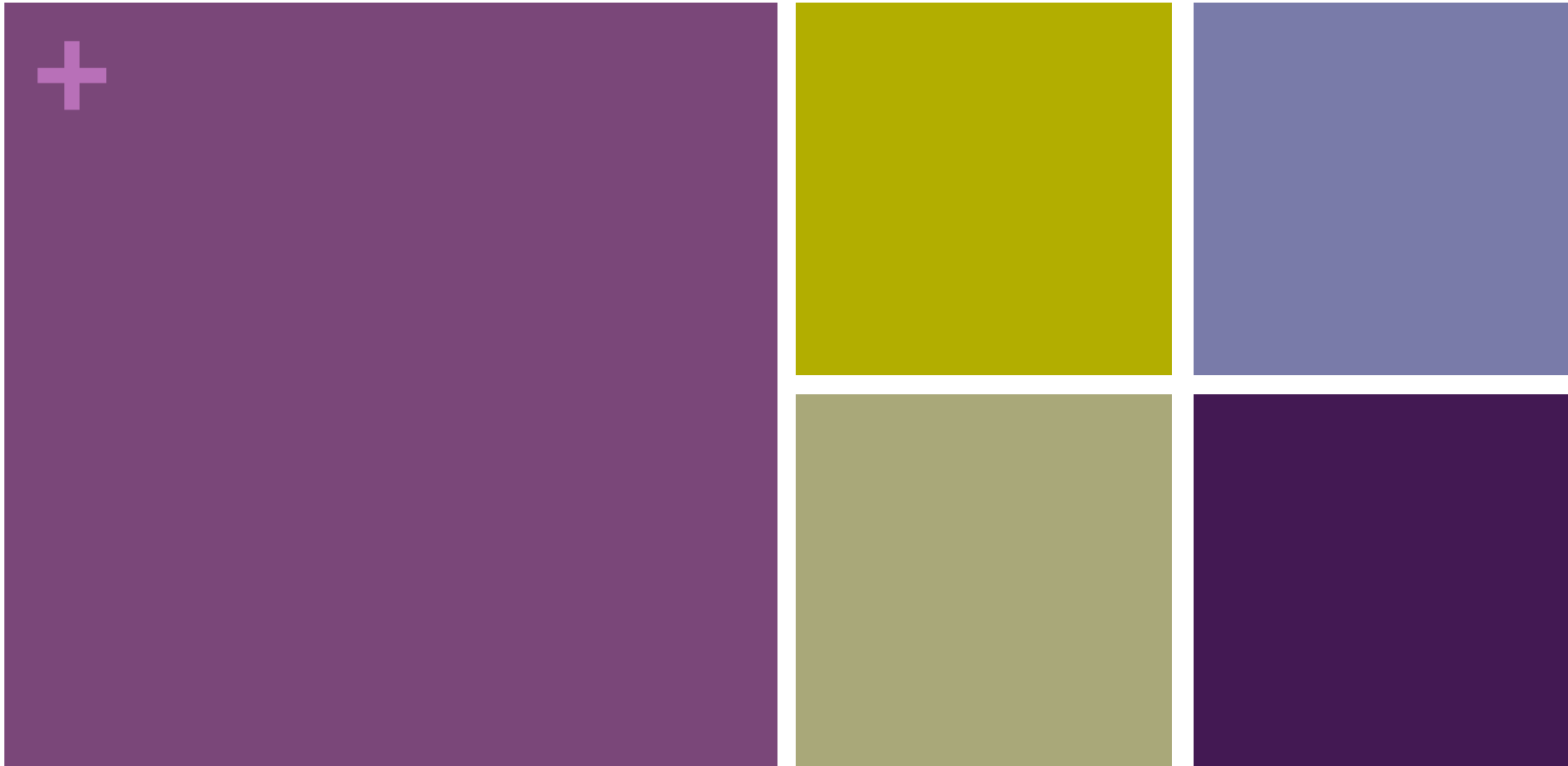
Rev. Sci. Instrum. 66,  
5477 (1995)



UHV-compatible 7 Si(Li) SSD

UHV 8-axis goniometer

UHV XAS system with MBE

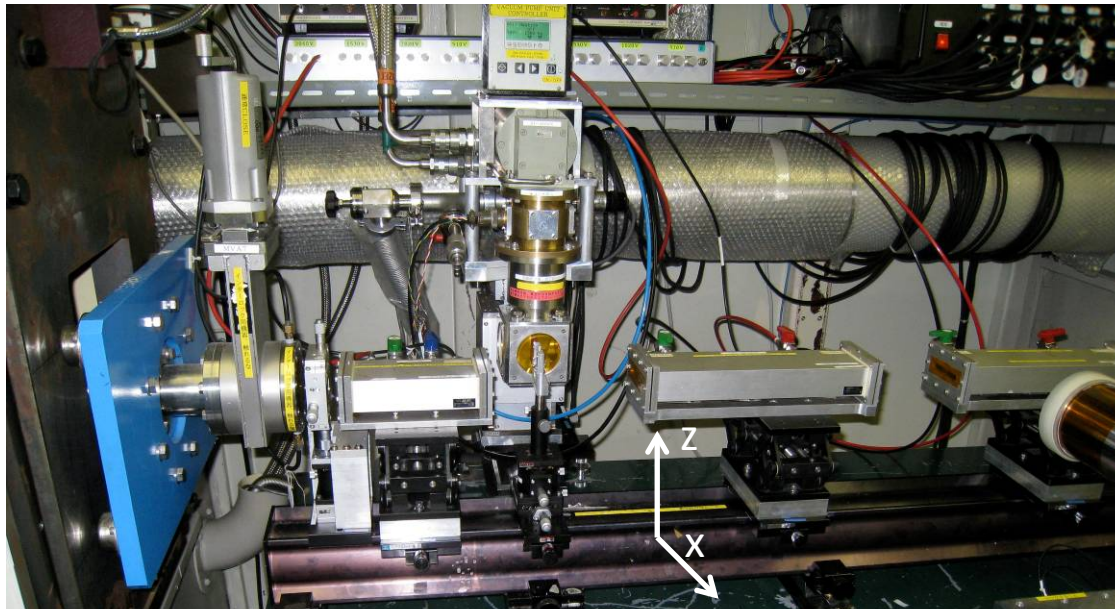


## Sample preparation methods

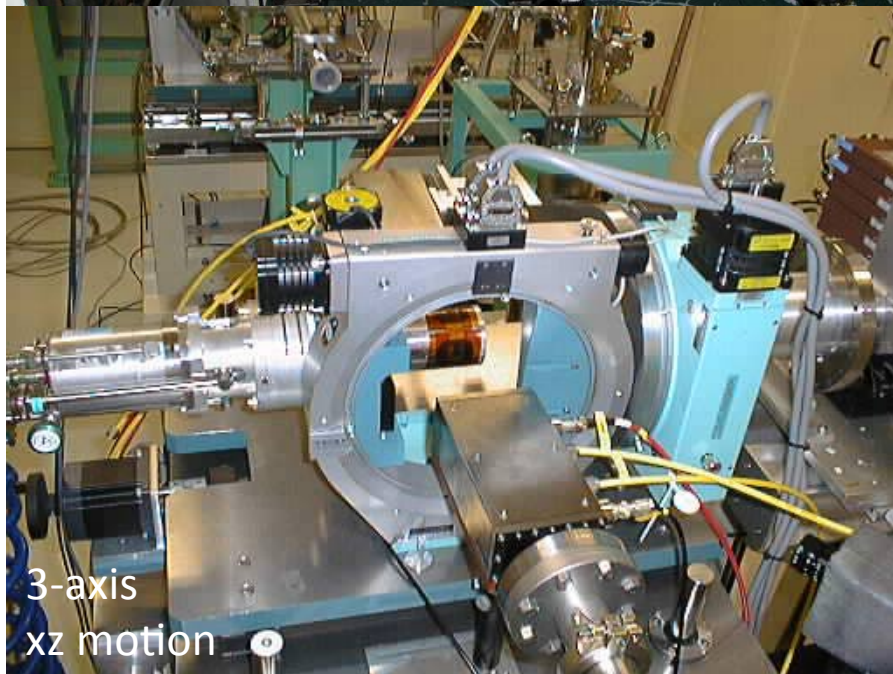
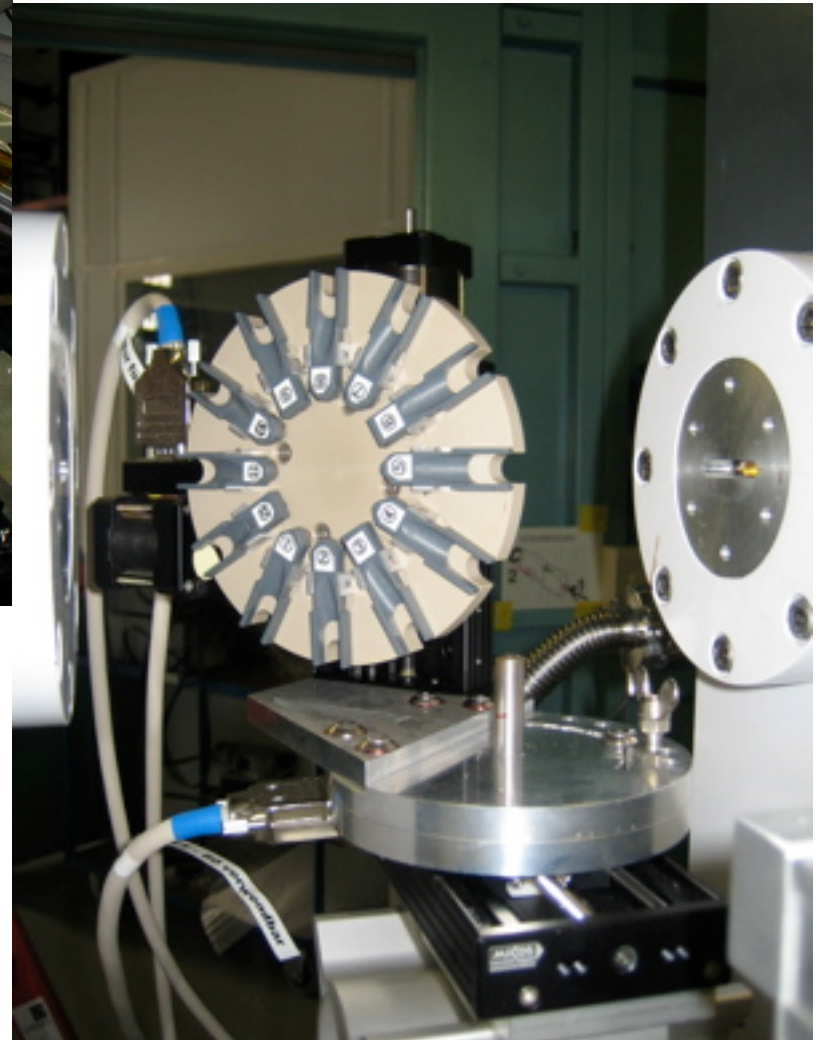
Some hints for better experiments

# + Cryostat

Closed cycle He cryostat @KEK



Multi sample holder  
@ANKA



Closed cycle He cryostat with flexible tube  
@SPring8

# + Sample preparation

## General

Detailed description of sample preparation is available at [xafs.org](http://xafs.org) by the following researchers

Grant Bunker  
Matt Newville  
Rob Scarrow  
Scott Calvin

*URLs for each description available at [xafs.org](http://xafs.org)*

## Transmission experiment (Powder specimen)

<http://www.xafs.org/Experiment/DoublyContainedSamples>

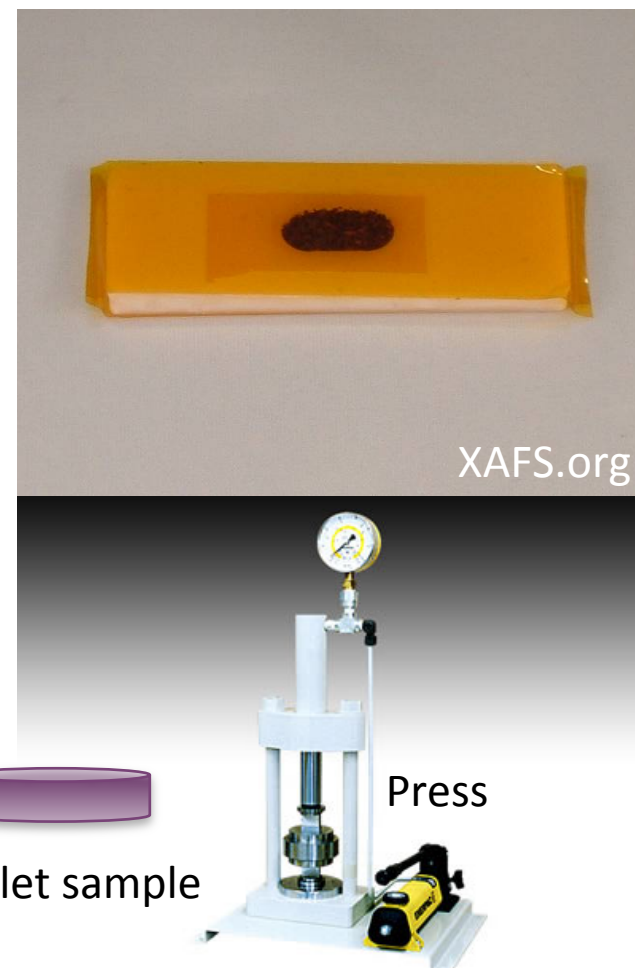
Homogeneity and right thickness/concentration

## Fluorescence experiment (single crystal)

Orientation and surface roughness

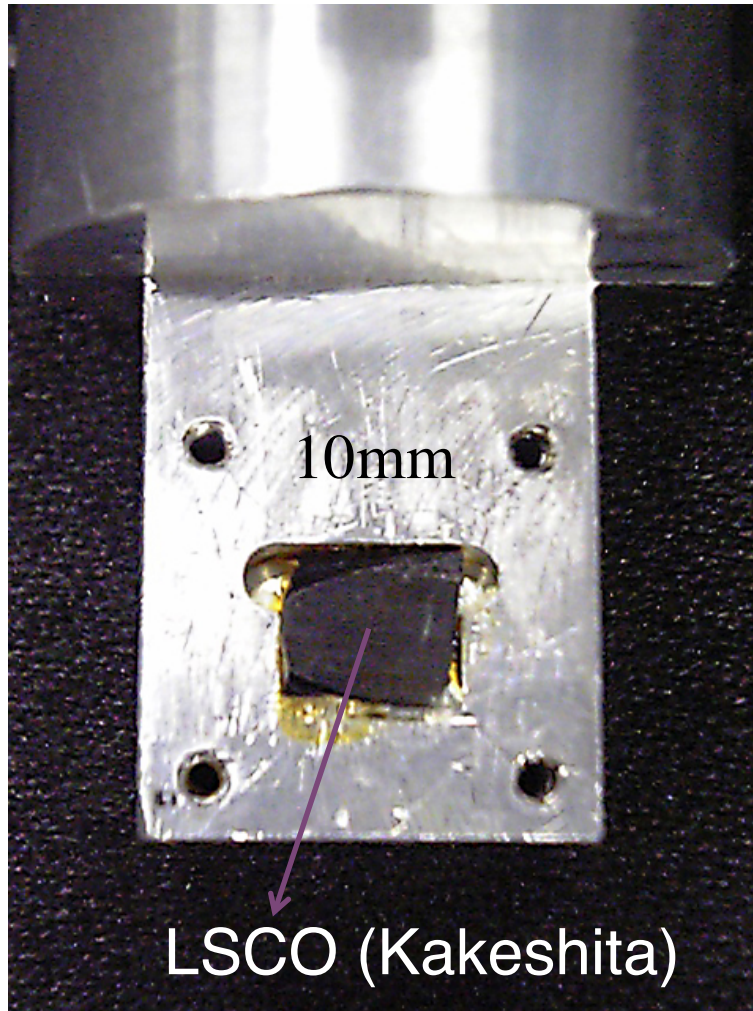
## Temperature dependence

Stress-free good thermal contact



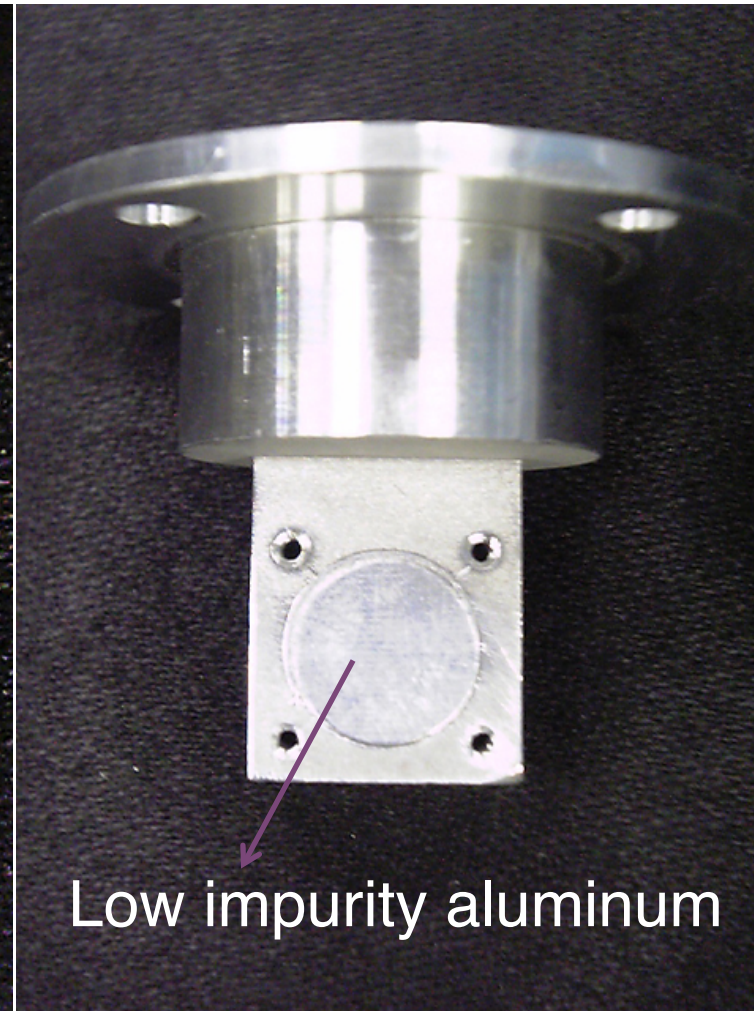
## + Sample mounting (bulk single crystals)

Large single crystal mounted on an aluminum base (left), smaller crystal mounted on impurity-free base (right)



LSCO on a standard type

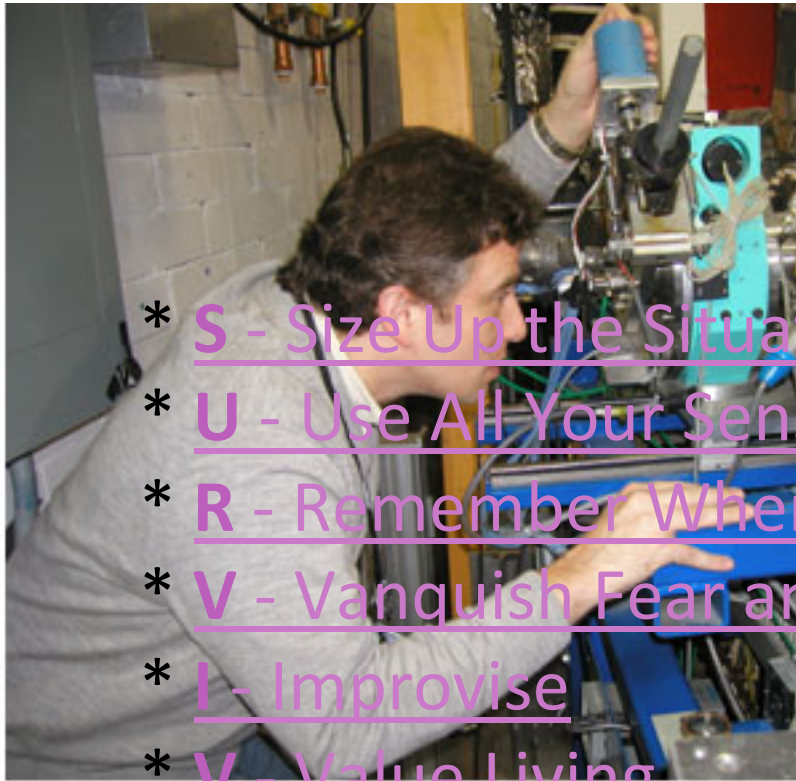
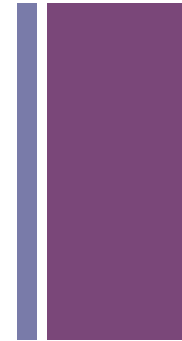
2-4mm



Low-impurity type

1mm or less

## + Enjoy your experiment –Survival tips



- \* S - Size Up the Situation
- \* U - Use All Your Senses, Undue Haste Makes Waste
- \* R - Remember Where You Are
- \* V - Vanquish Fear and Panic
- \* I - Improvise
- \* V - Value Living
- \* A - Act Like the Natives
- \* L - Live by Your Wits, *But for Now, Learn Basic Skills*

Anatoly Fronkel at NSLS beam line X16C.



*taken from the U.S. Army Survival Manual*